



# OPTICAL PROPERTIES OF **SILICON** FOR CRYOGENIC GW DETECTORS

ZENO TORNASI

11/07/2017 - HILTON HOTEL, PASADENA, CA, U.S.A.

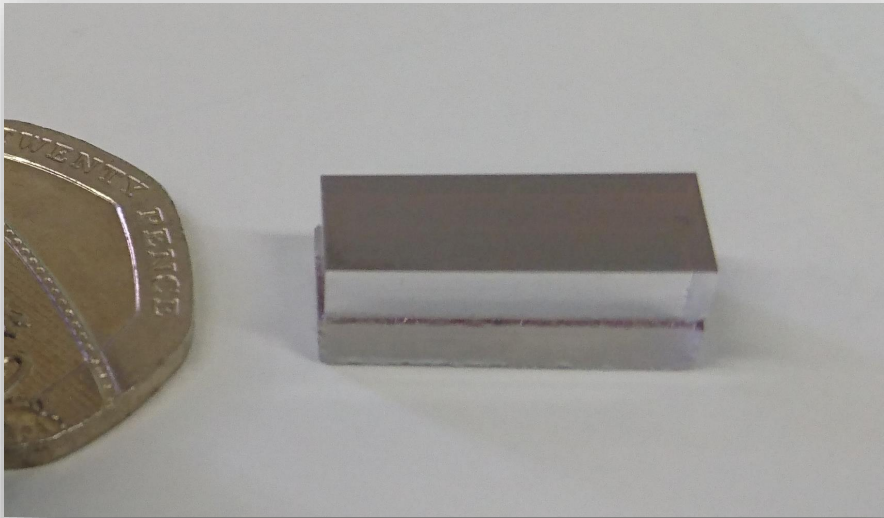
R. Adhikari<sup>1</sup>, A. Bell<sup>2</sup>, R. Birney<sup>3</sup>, M. Fejer<sup>4</sup>, D. Gibson<sup>3</sup>,  
E. Gustafson<sup>1</sup>, J. Hough<sup>2</sup>, A. Markosyan<sup>4</sup>, I. W. Martin<sup>2</sup>,  
J. Steinlechner<sup>2,5</sup>, S. Reid<sup>3</sup>, S. Rowan<sup>2</sup>, S. Sproules<sup>2</sup>

<sup>1</sup>CALTECH, <sup>2</sup>UofG, <sup>3</sup>UWS, <sup>4</sup>STANFORD, <sup>5</sup>HAMBURG



# Crystalline silicon

## Optical scattering



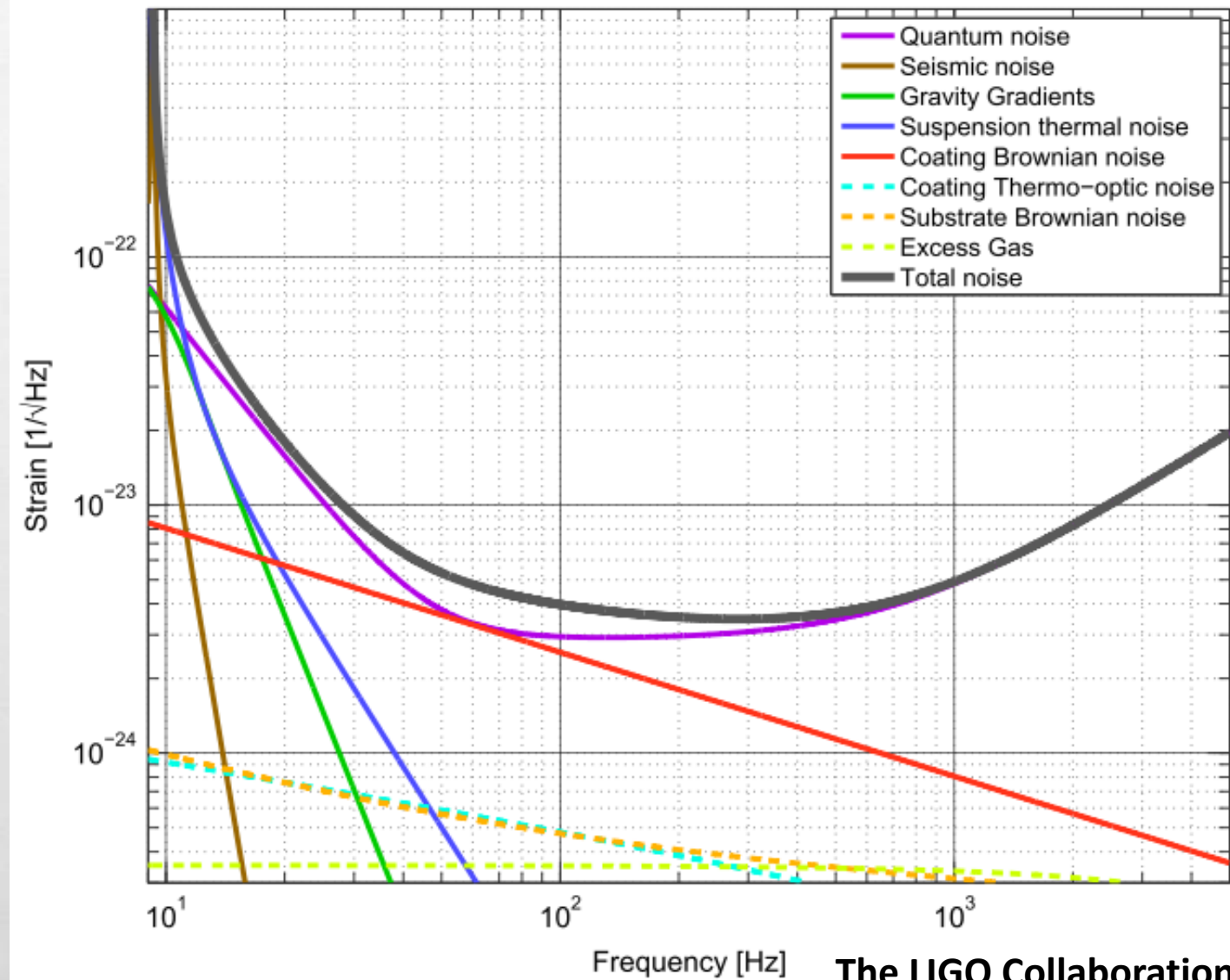
# Amorphous silicon coatings

## Optical absorption

# Topics

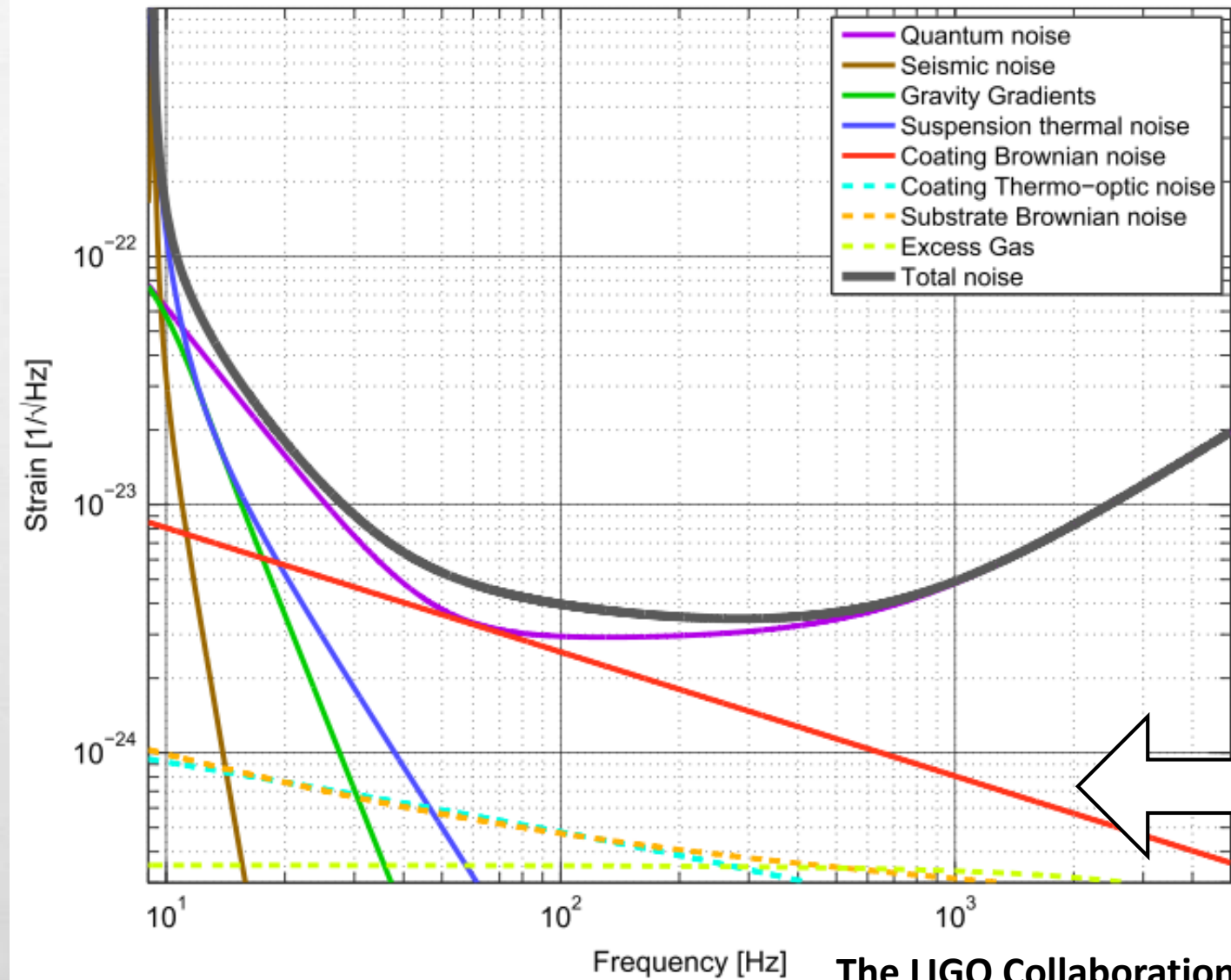
# Why silicon?

## Introduction



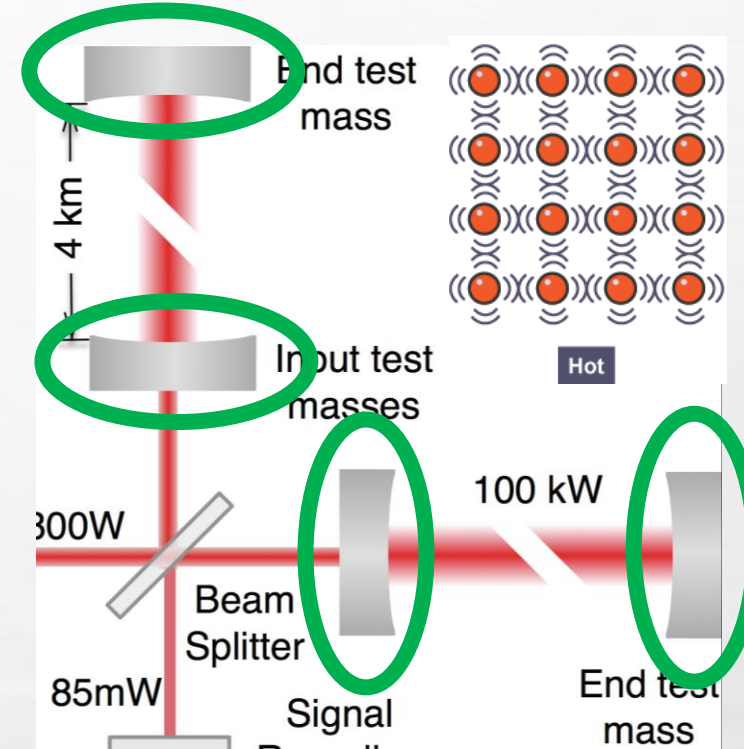
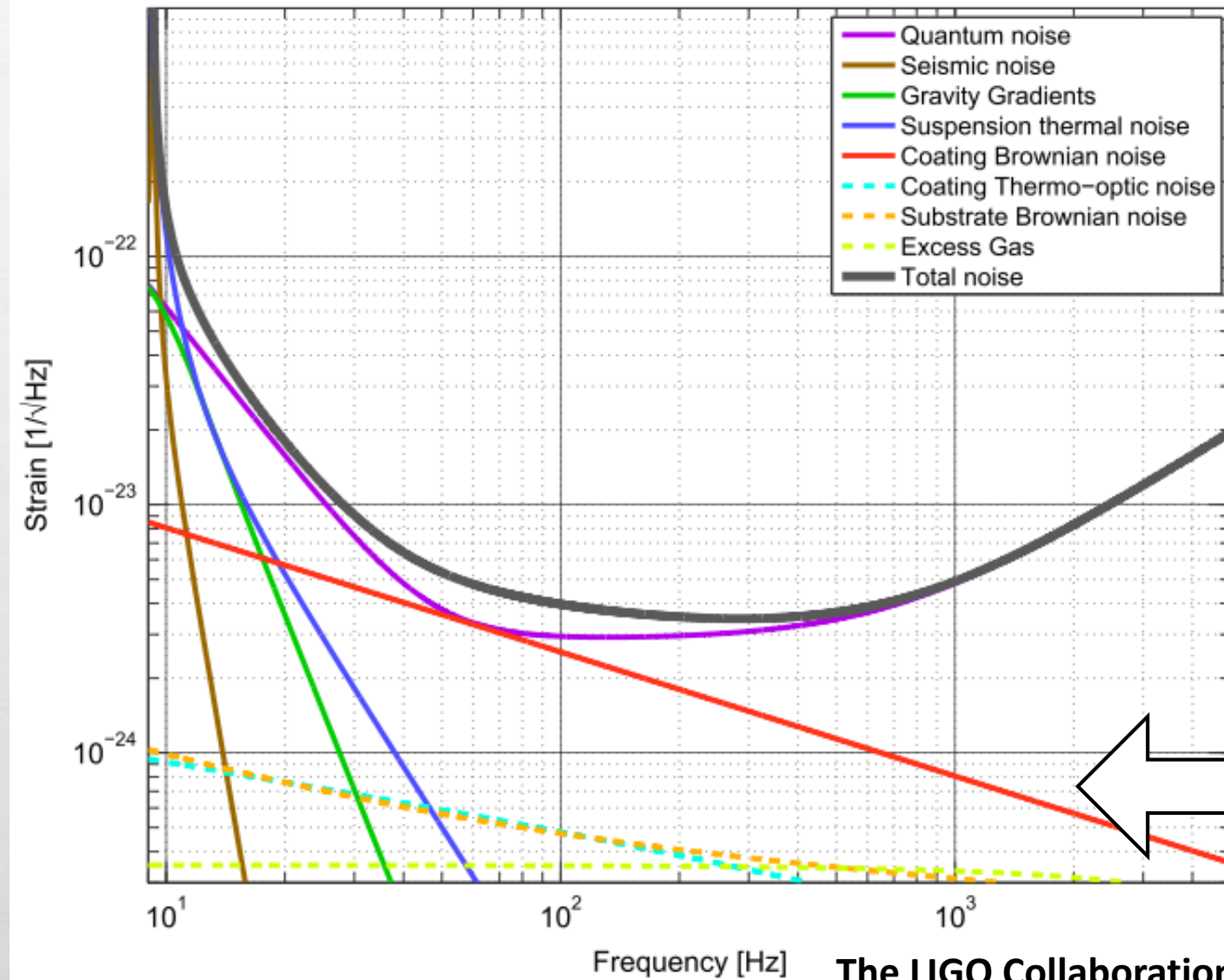
The LIGO Collaboration, Class. Quantum Grav. 32 (2015) 074001

# Noise in a gravitational wave detector



The LIGO Collaboration, Class. Quantum Grav. 32 (2015) 074001

# Noise in a gravitational wave detector



**Coating  
Brownian  
noise**

The LIGO Collaboration, Class. Quantum Grav. 32 (2015) 074001

# Noise in a gravitational wave detector

$$S_x(f) \propto \frac{T \phi d}{f Y w^2}$$

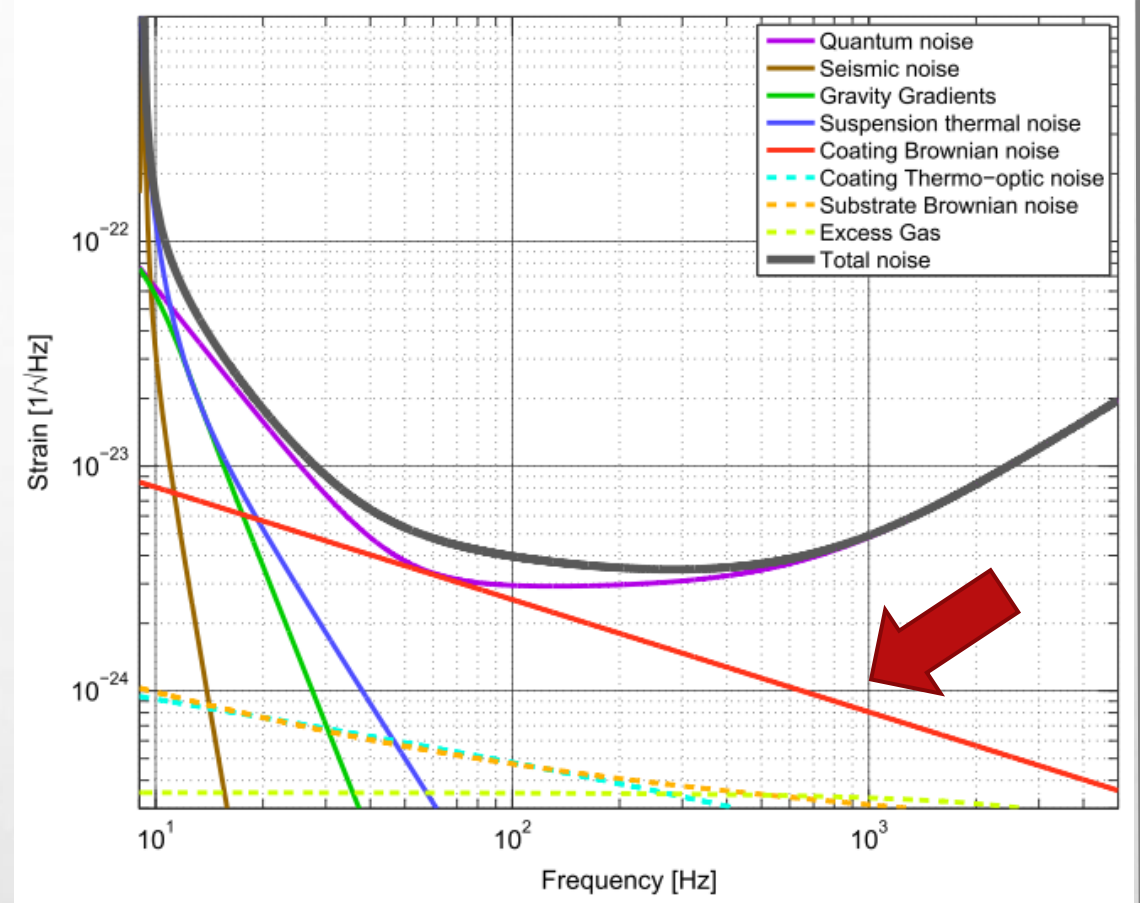
Temperature

Mechanical loss

Coating thickness

Young's modulus

Beam width



**Coating Brownian noise (similar idea for substrates)**

$$S_x(f) \propto \frac{T \phi d}{f Y w^2}$$

Temperature

Mechanical loss

Coating thickness

Young's modulus

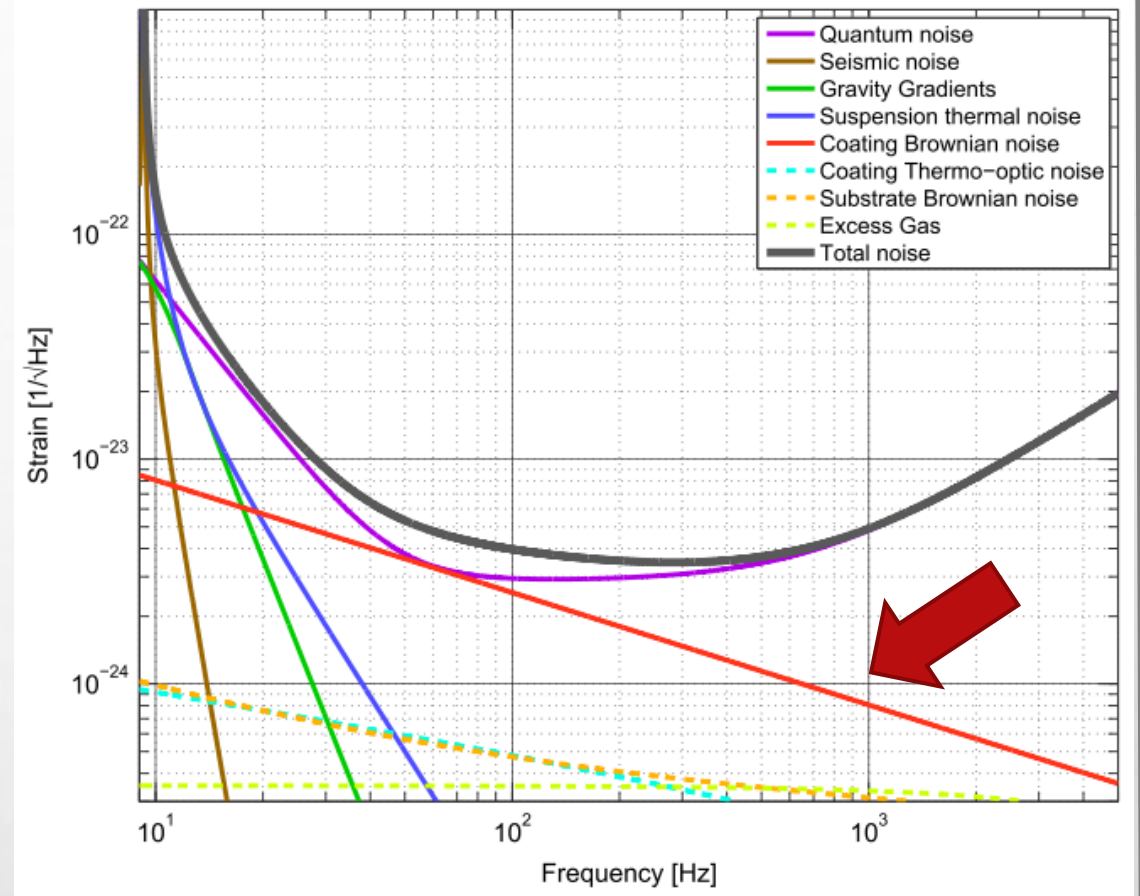
Beam width



Limited room for improvement

Substrate engineering constraints

**Coating Brownian noise (similar idea for substrates)**





$$S_x(f) \propto \frac{T \phi d}{f Y w^2}$$

Temperature

Mechanical loss

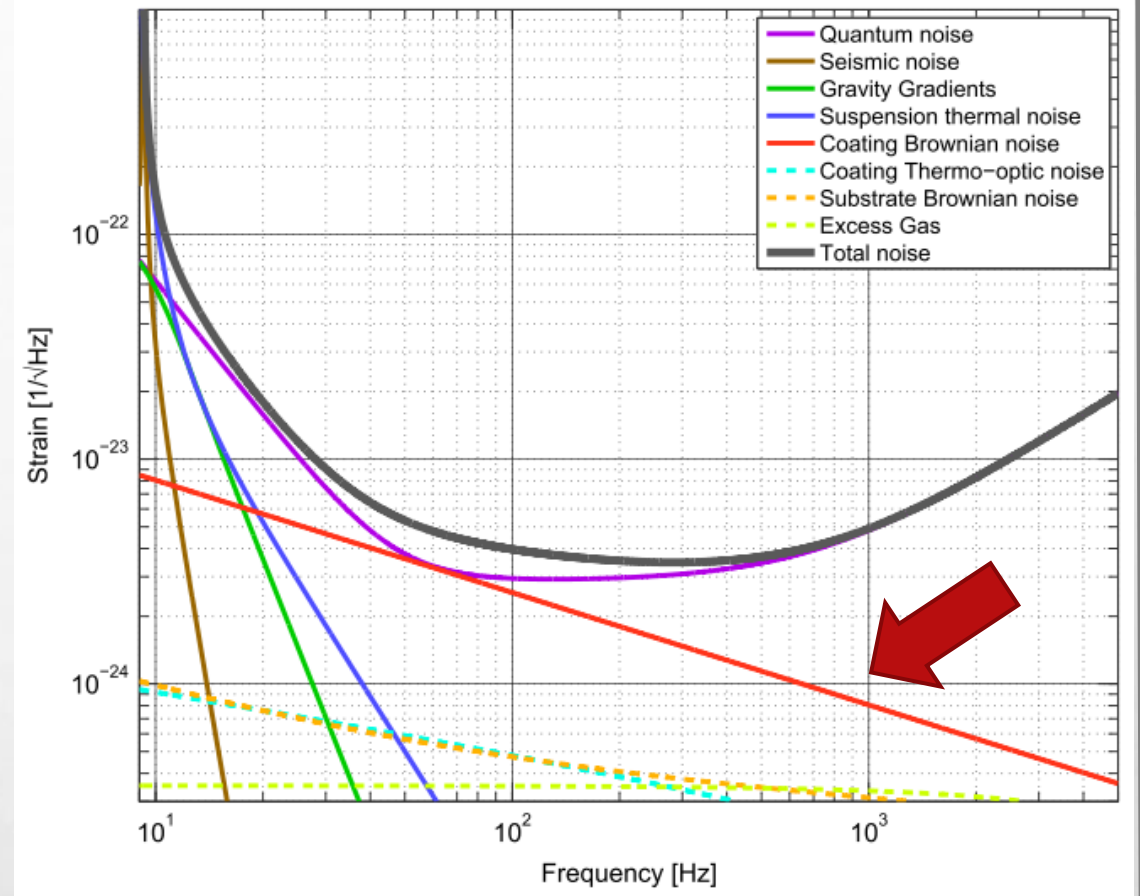
Coating thickness

Young's modulus

Beam width



Property of the coating material  
Not much to do about it



**Coating Brownian noise (similar idea for substrates)**

$$S_x(f) \propto \frac{T \phi d}{f Y w^2}$$

Temperature

Mechanical loss

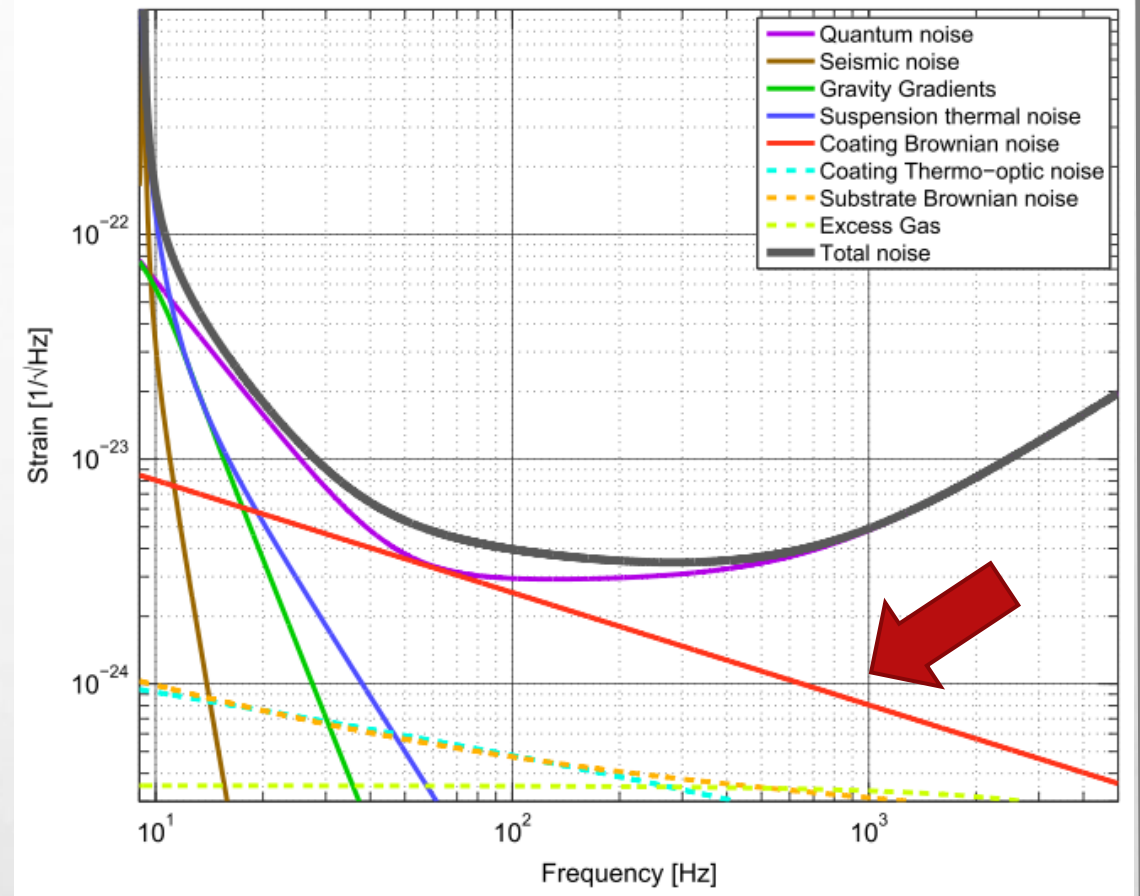
Coating thickness

Young's modulus

Beam width



High refractive index materials



**Coating Brownian noise (similar idea for substrates)**

$$S_x(f) \propto \frac{T \phi}{f Y}$$

Temperature

Mechanical loss

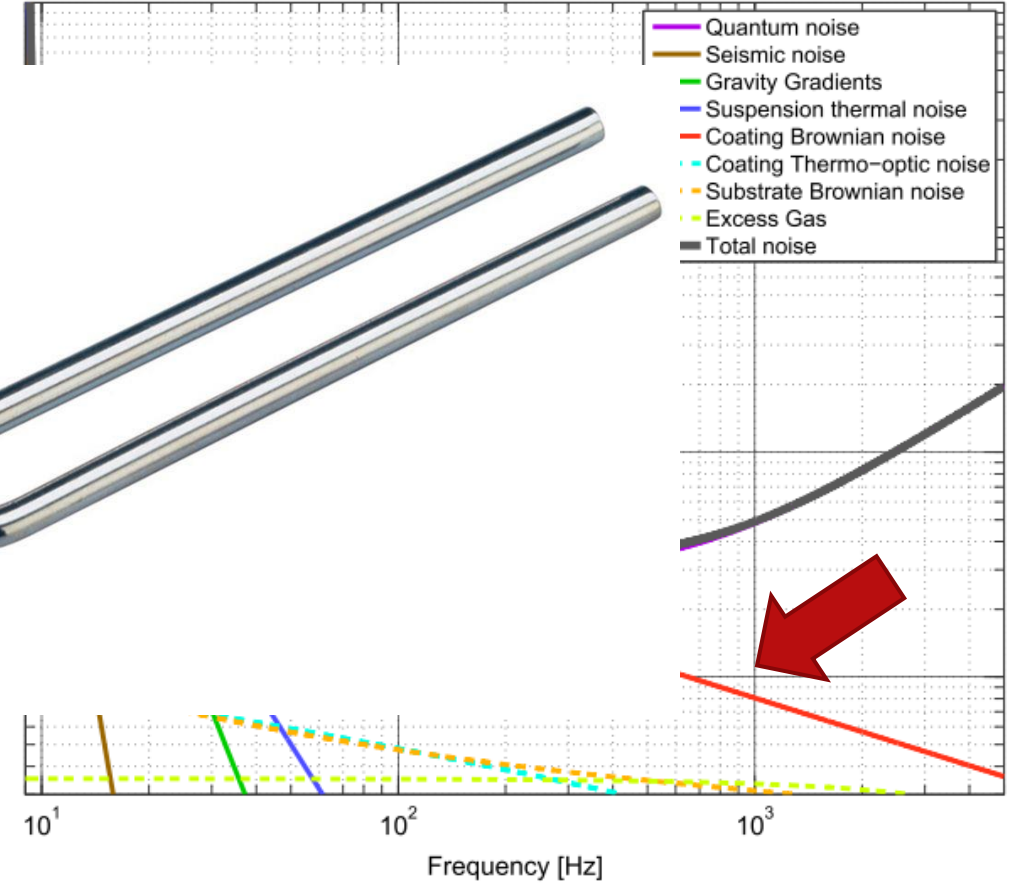
Coating thickness

Young's modulus

Beam width



Property of the material  
 Can vary by orders of magnitude  
 Can be engineered to some extent



**Coating Brownian noise (similar idea for substrates)**

$$S_x(f) \propto \frac{T \phi d}{f Y w^2}$$

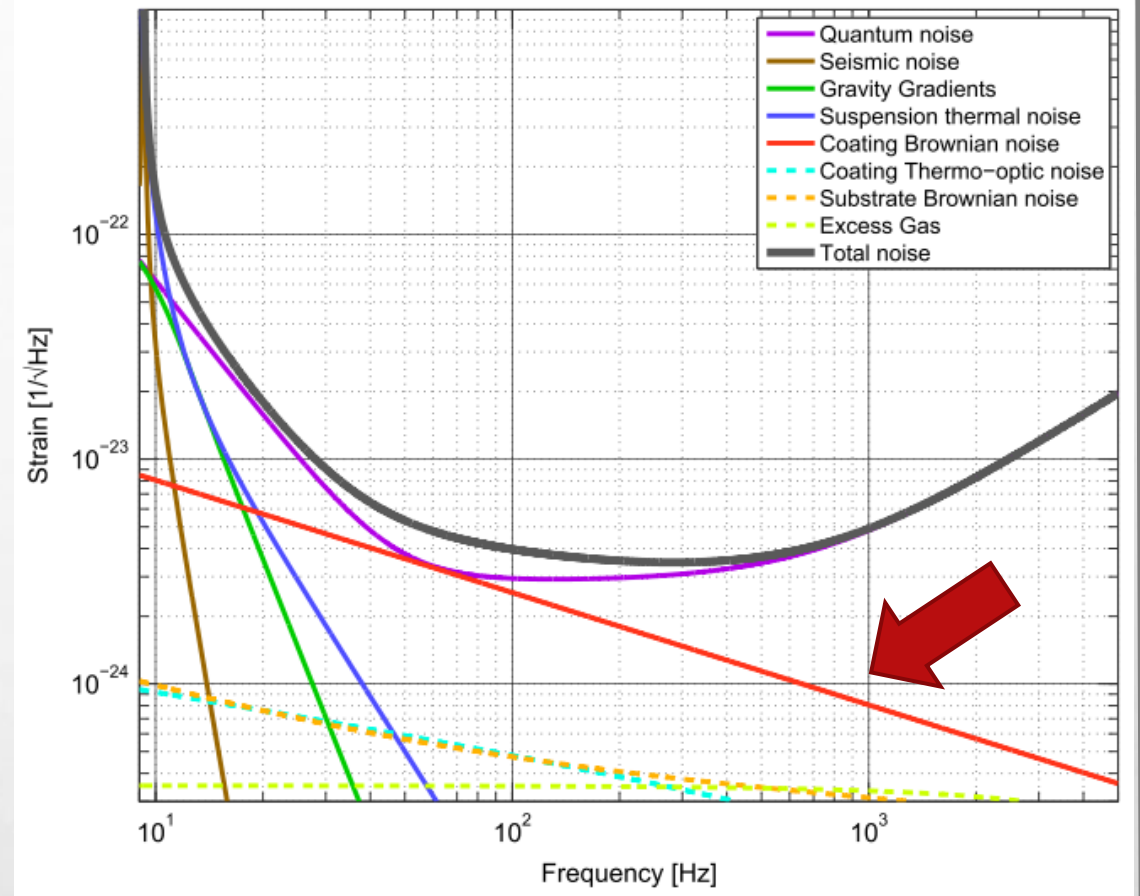
Temperature

Mechanical loss

Coating thickness

Young's modulus

Beam width



Current detectors operate at room T  
Can we just go cryogenic then? Not yet...

**Coating Brownian noise (similar idea for substrates)**

- In general

$$S_x(f) \propto \frac{T \phi d}{f Y w^2}$$

**Fused silica has a high mechanical loss at low T**

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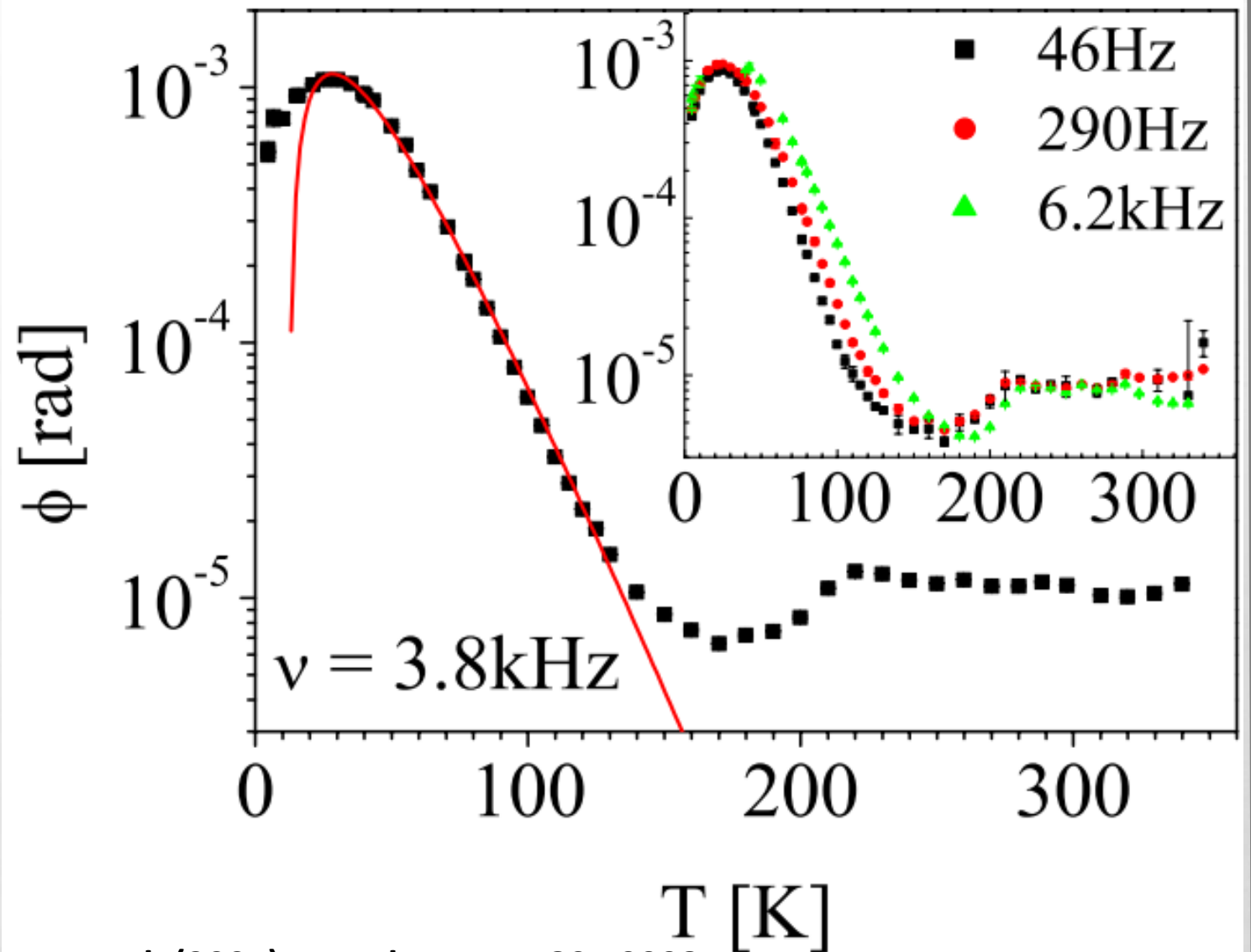
- Currently LIGO optics are made of fused SiO<sub>2</sub>

**Fused silica has a high mechanical loss at low T**

- In general

$$S_x(f) \propto \frac{T \phi(T) d}{f Y w^2}$$

- Currently LIGO optics are made of fused SiO<sub>2</sub>
- Since the '50s we know that mechanical loss in SiO<sub>2</sub> goes like →→→



Travasso F. et al. (2007) Europhys. Lett. 80 50008

**Fused silica has a high mechanical loss at low T**



Fused silica is used



As a substrate



As a coating

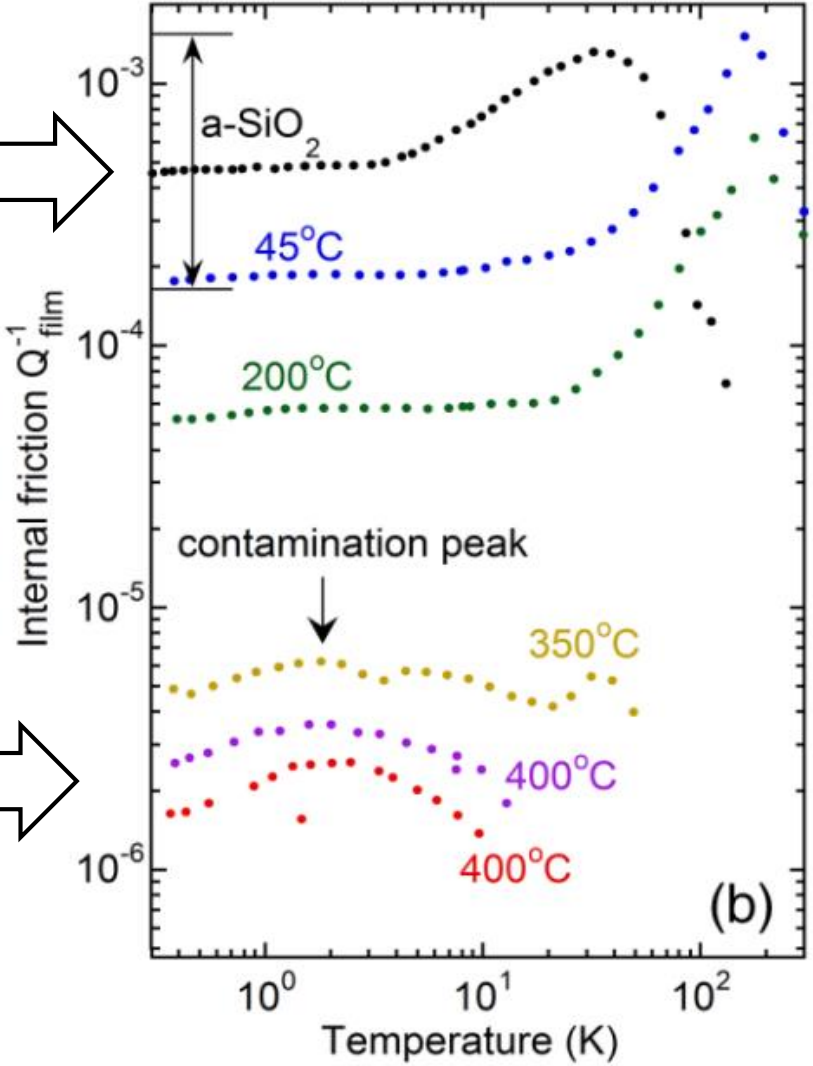
With tantala (also lossy at low T)

WHAT DO WE USE INSTEAD?

**THE PROBLEM**

**SiO<sub>2</sub>**

**aSi**

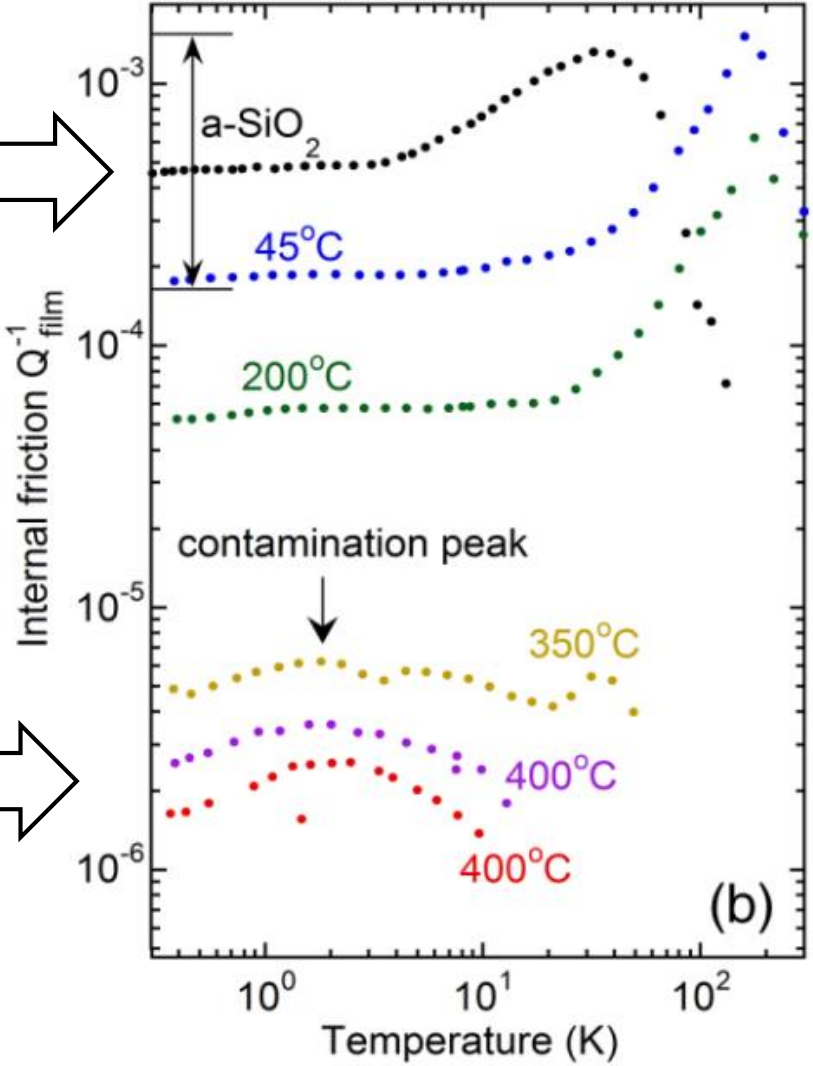


X. Liu, F. Hellman, et al, *PRL* 113, 025503 (2014)

# Coatings: Amorphous silicon looks promising

**SiO<sub>2</sub>**

**aSi**



**Bonus**  
High refractive index  
 $n = 3.47 @ 1550 \text{ nm}$   
helps reducing thickness

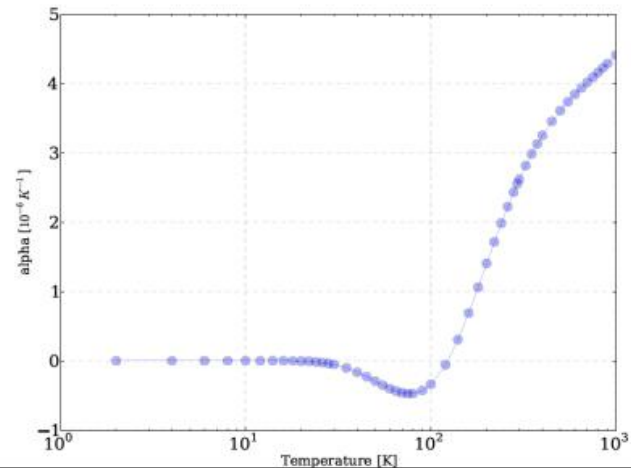
X. Liu, F. Hellman, et al, *PRL* 113, 025503 (2014)

**Coatings: Amorphous silicon looks promising**

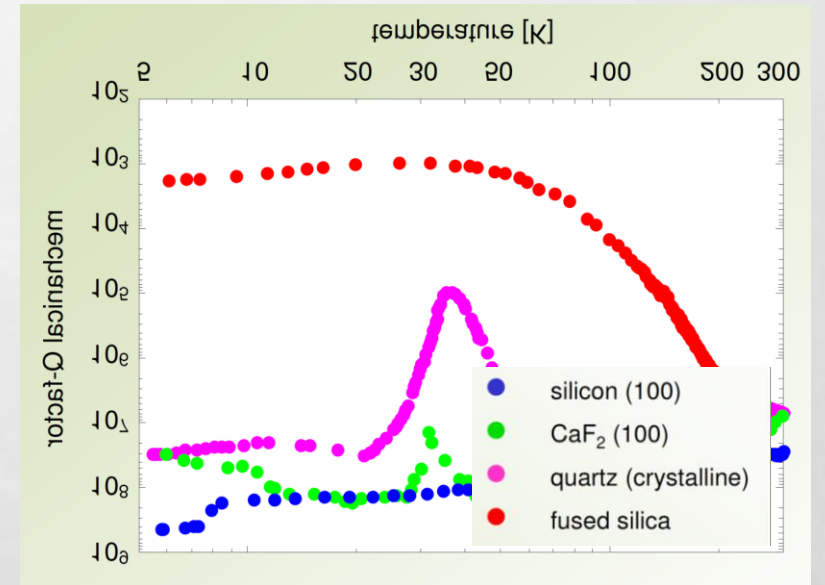
# SEDUCTION OF SILICON



- Analogous to sapphire
  - (and various other crystalline materials)
  - No cryogenic loss peak
  - High thermal conductivity (and TE noise)
- But thermal expansion coeff  $\alpha \rightarrow 0$  for  $T \sim 120$  K,  $T \lesssim 20$  K
- Thermal deformation and TE noise vanish at those temperatures
- Also, cryogenics at 120 K can cope with heat load from **high circulating power**



We know since the '70s that cSi has very low **mechanical loss** at **low temperature**.



Credits: Ronny Nawrodt

**Substrates: Crystalline silicon looks great too**

Both cSi and aSi have low mechanical loss at low temperature

But what about optical properties?

	cSi (bulk)	cSi (surface)	aSi
Absorption	A. Bell, A. Markosyan	Ongoing (A. Bell)	This work
Scattering	This work	Future work?	Future work

Recap



# Crystalline silicon

# 1. Standard Czochralski grown silicon (Cz Si)

Too impure for application in GW detectors because of high optical absorption **x**



A. Markosyan, A. Bell / LIGO-G1700480

# 2. Float-zone silicon (FZ Si)

Very pure and low absorbing: 2 ppm/cm @ 1550 nm **✓**

Available in crystals of maximum diameter 20 cm **x**

# 3. Magnetic field-grown Czochralski silicon (MCz Si)

Available up to 45 cm in diameter **✓**

Bulk absorption can be as low as 5 ppm/cm @ 1550 nm, albeit inhomogeneous **✓**

Surface absorption is a different beast  
A. Bell / LIGO-P1700134

# Crystalline silicon bulk absorption

**Photons scattered  
off axis**

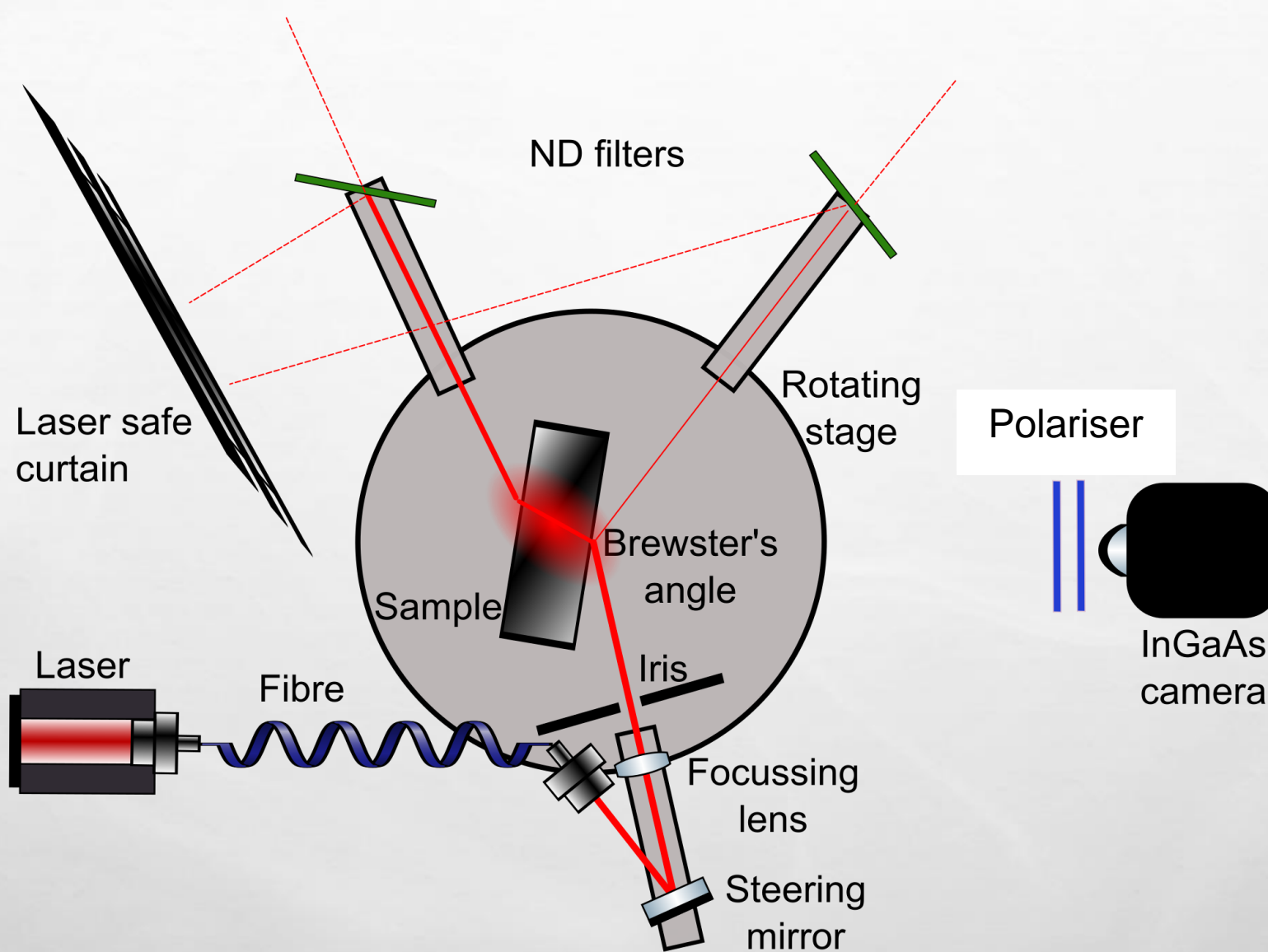
**Add phase noise if  
they are reflected  
back in the system by  
the environment**

**Contribute to cavity  
round trip loss**

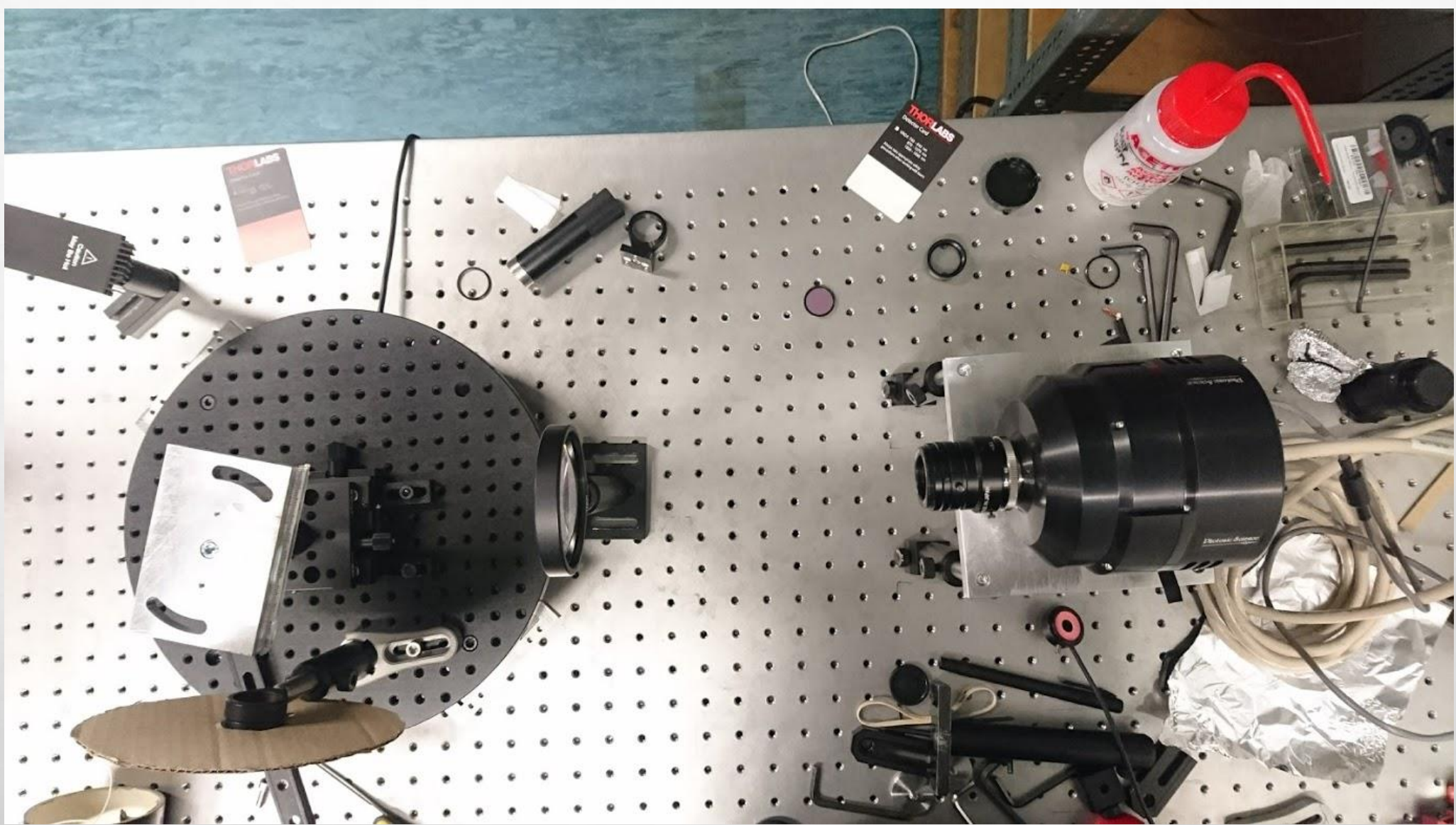
**Easily disrupt  
squeezed states**

**Why scattering matters**

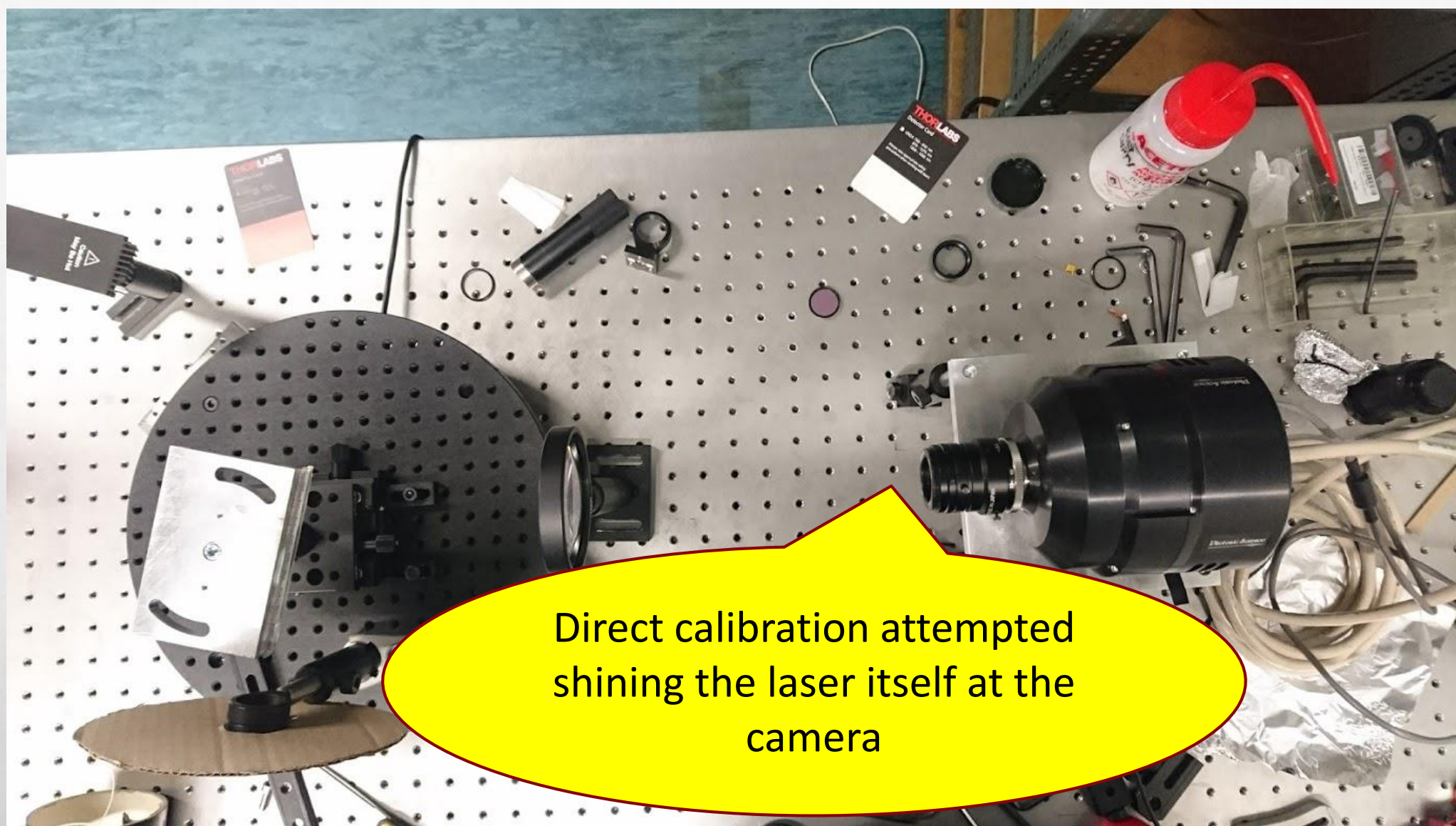




# The Glasgow scatterometer



# The Glasgow scatterometer

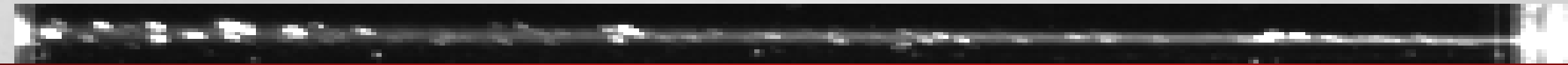
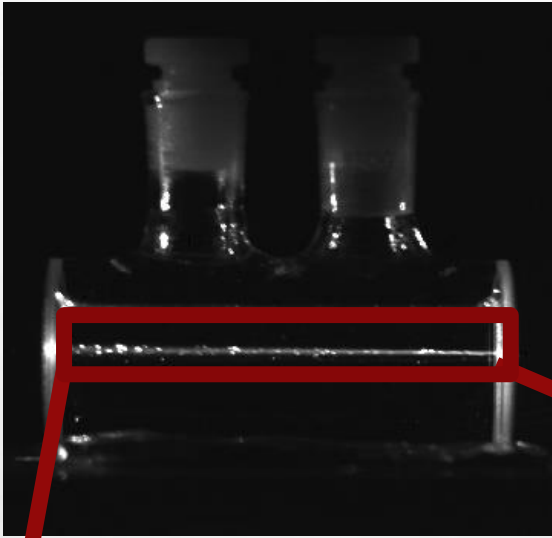


Direct calibration attempted  
shining the laser itself at the  
camera

# The Glasgow scatterometer



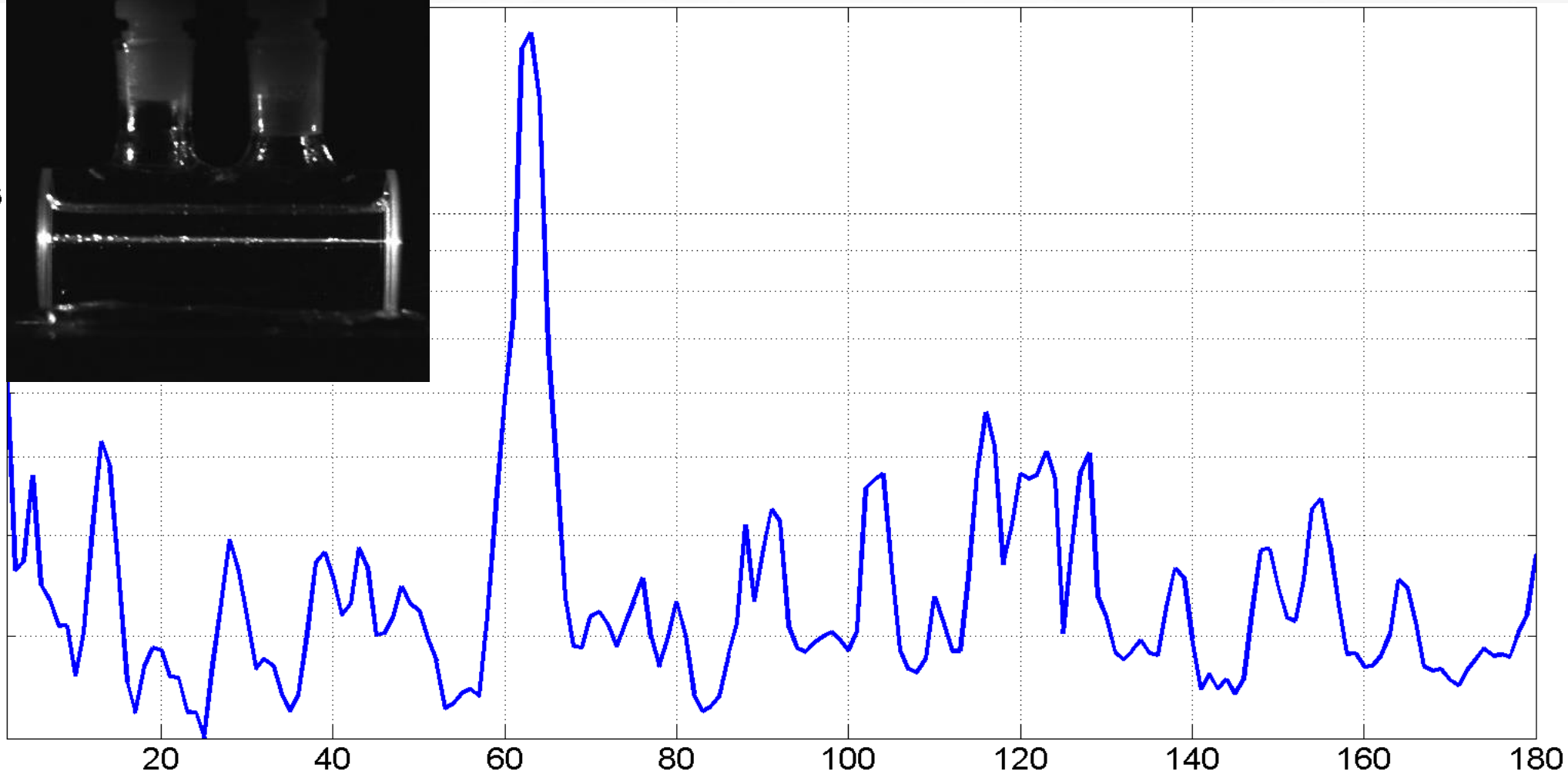
**“Engineering run 1”: looking at  $\text{CCl}_4$**



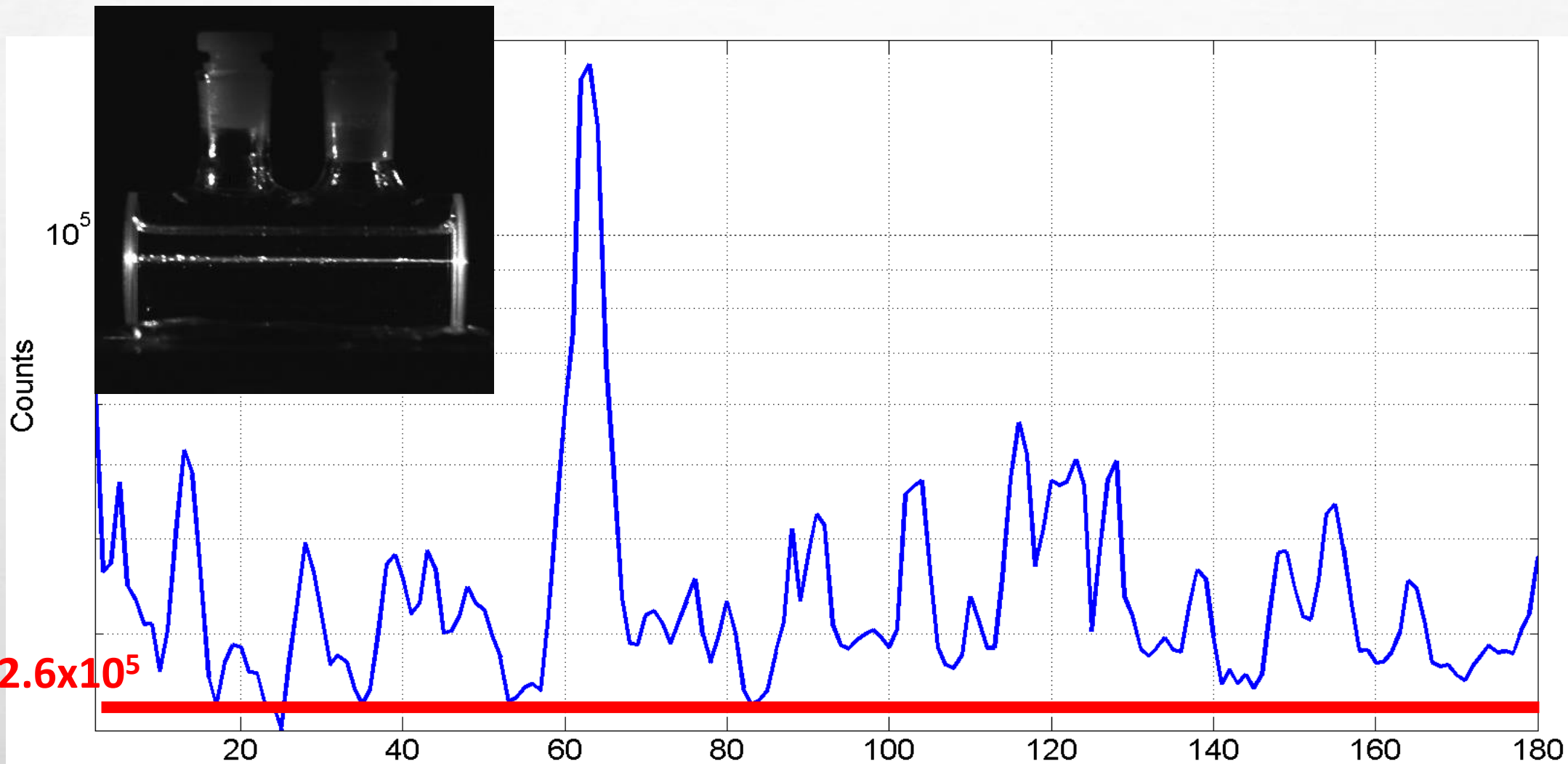
**“Engineering run 1”: looking at  $\text{CCl}_4$**

Counts

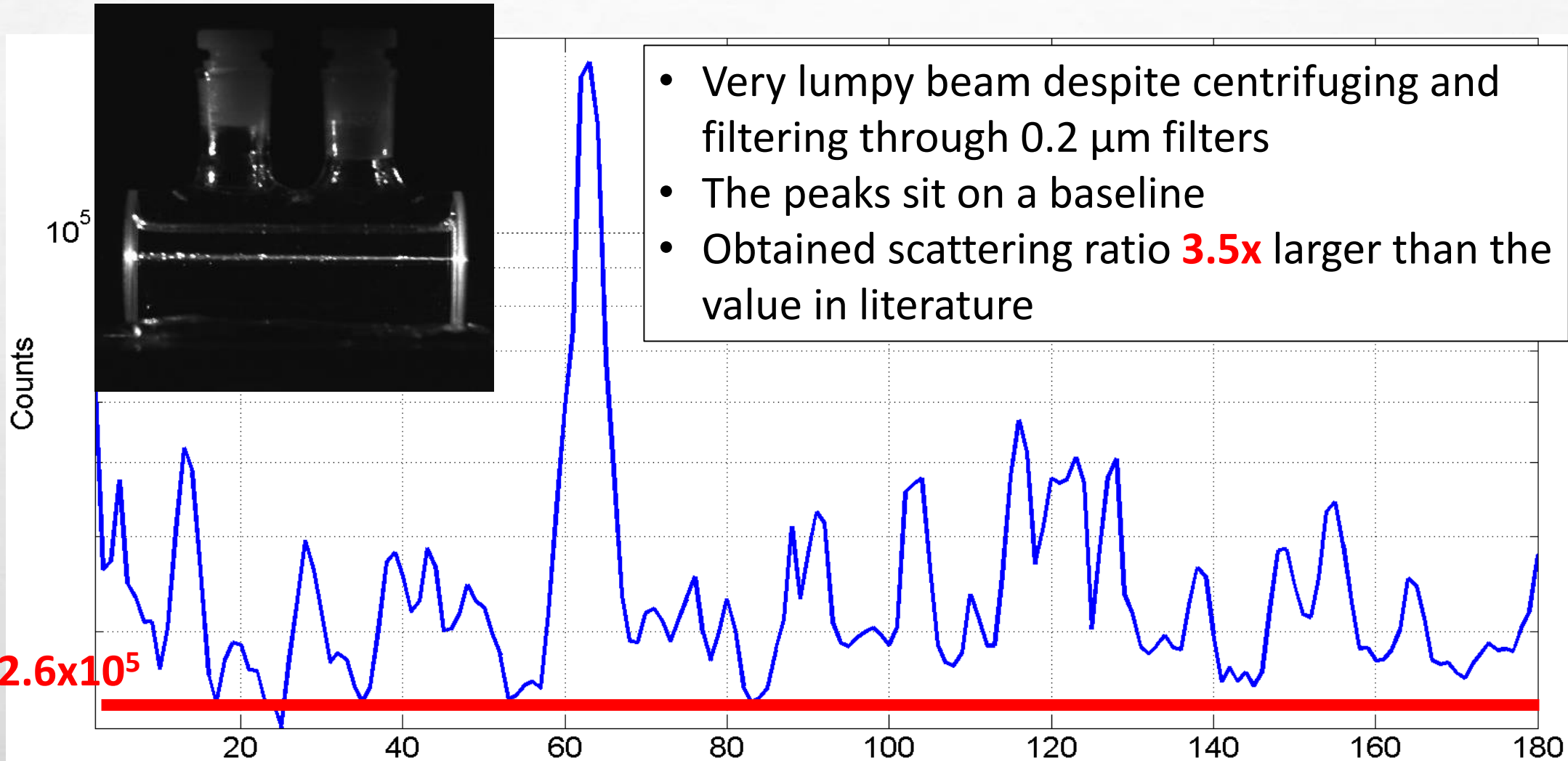
$10^5$



**“Engineering run 1”: looking at  $\text{CCl}_4$**

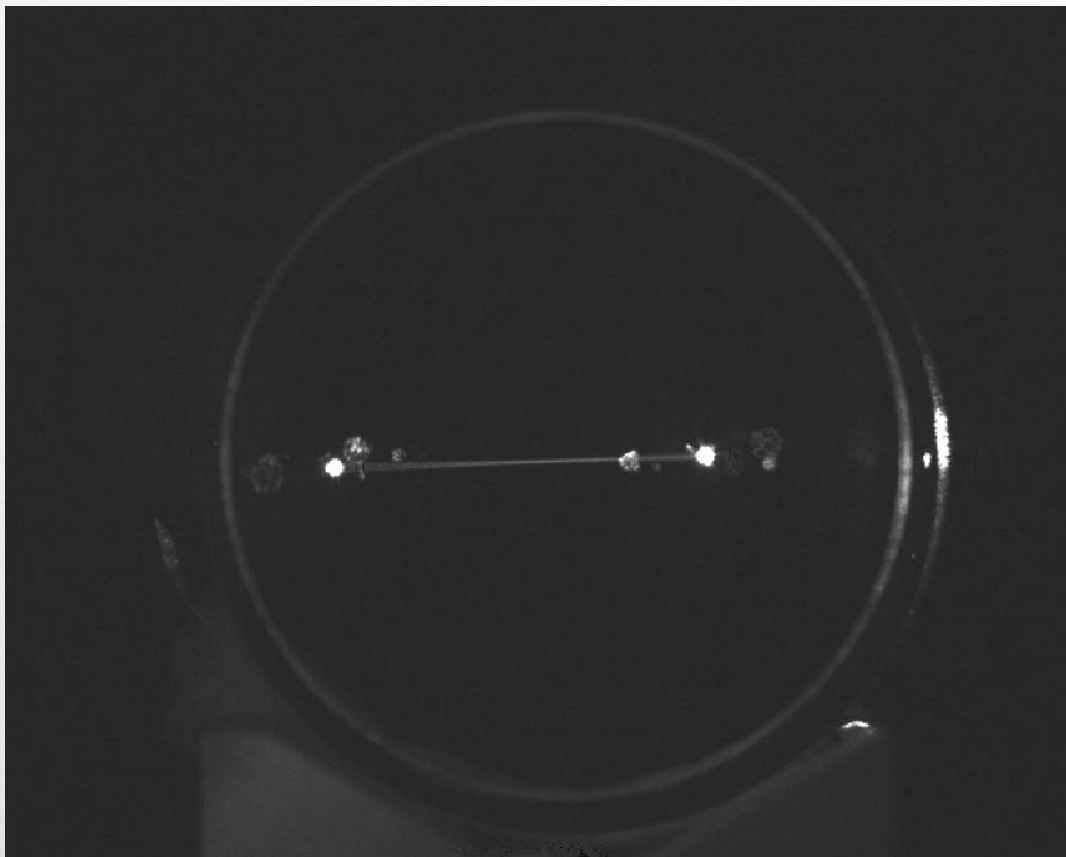


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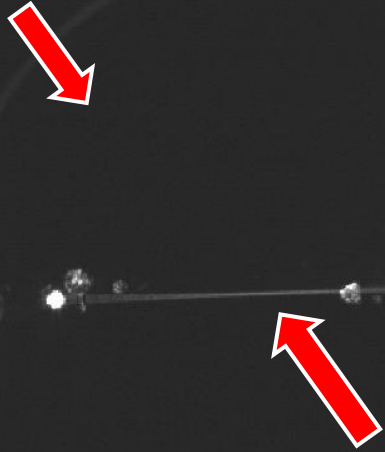




Heraeus Suprasil 3001  
fused silica cylinder  
(same silica used in aLIGO)

**“Engineering run 2”: fused silica**

Bulk silica cylinder viewed face-on

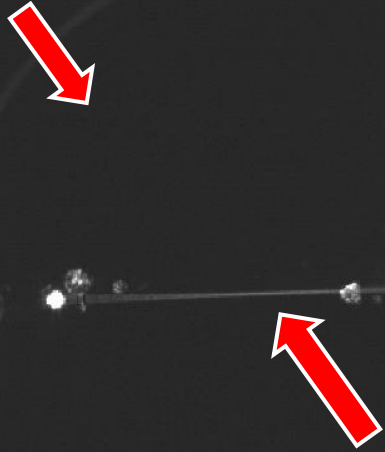


Beam in the medium  
and its reflections

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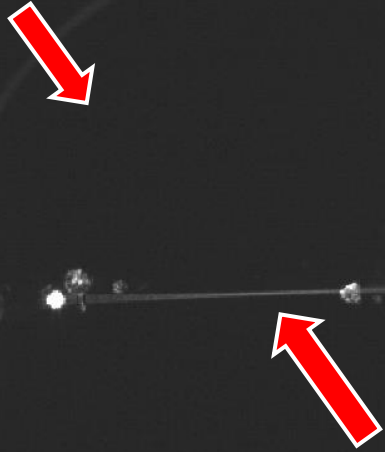
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## Difference between direct calibration and CCl4

- Scattering ratio obtained is **2.16x** larger than literature, according to my direct calibration
- Or it's **0.6x** literature, taking CCl4 as a reference

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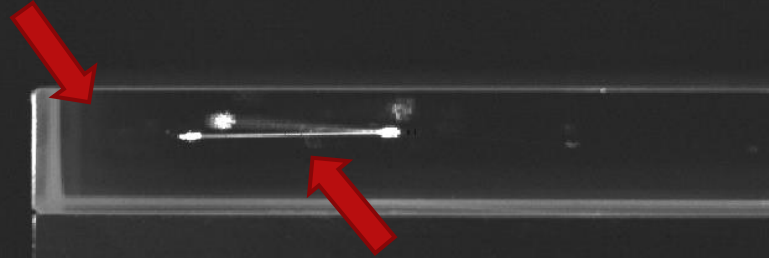
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- Or it's **0.6x** literature, taking CCl<sub>4</sub> as a reference

## Take away message

1. Still “commissioning” the scatterometer, plenty of things to understand better  
BUT
2. It's **NOT** off by orders of magnitude!

“Engineering run 2”: fused silica

Bulk MCz slab viewed face-on

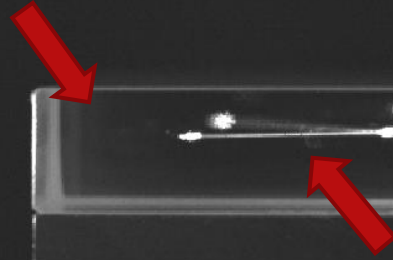


Beam in the medium  
and its reflections

Magnetic Czochralski  
silicon slab

**“O1”**: magnetic Czochralski silicon

Bulk MCz slab viewed face-on

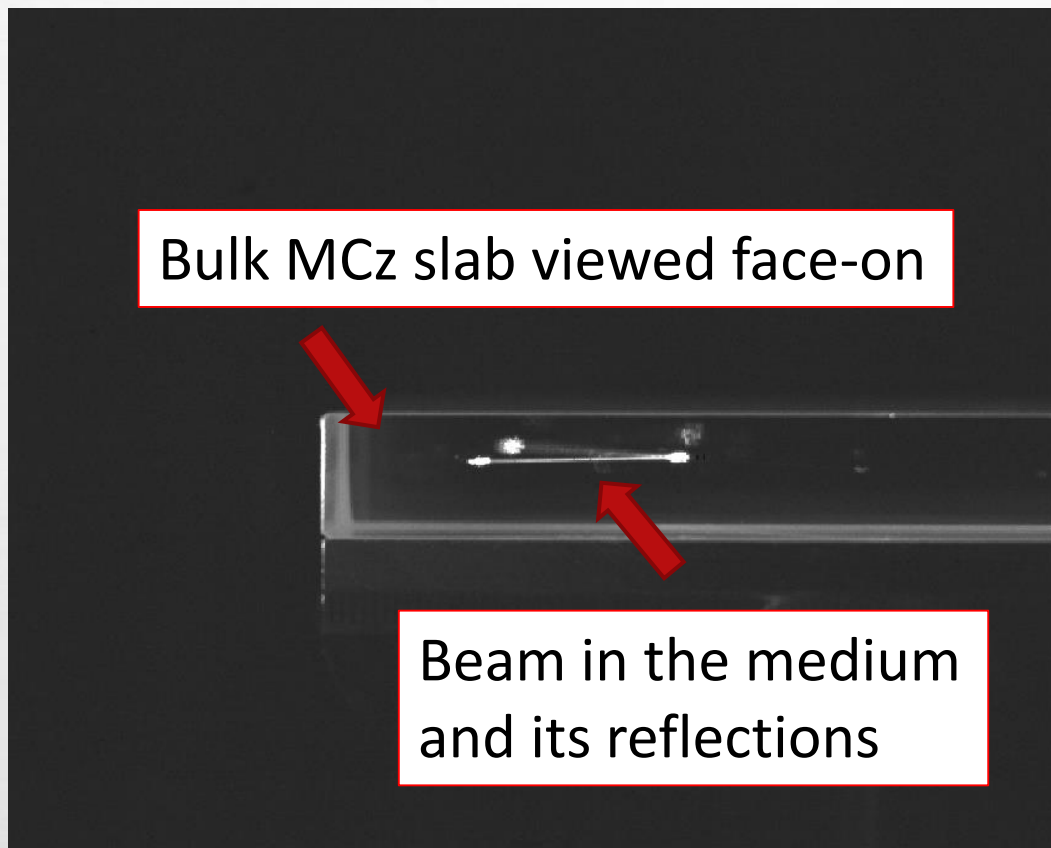


Beam in the medium  
and its reflections

- Difficult to isolate the main beam from the many strong reflections (high refr. index, small polished sample)
- Images **10** times brighter than fused silica under similar conditions.

Magnetic Czochralski  
silicon slab

**“O1”**: magnetic Czochralski silicon



Bulk MCz slab viewed face-on

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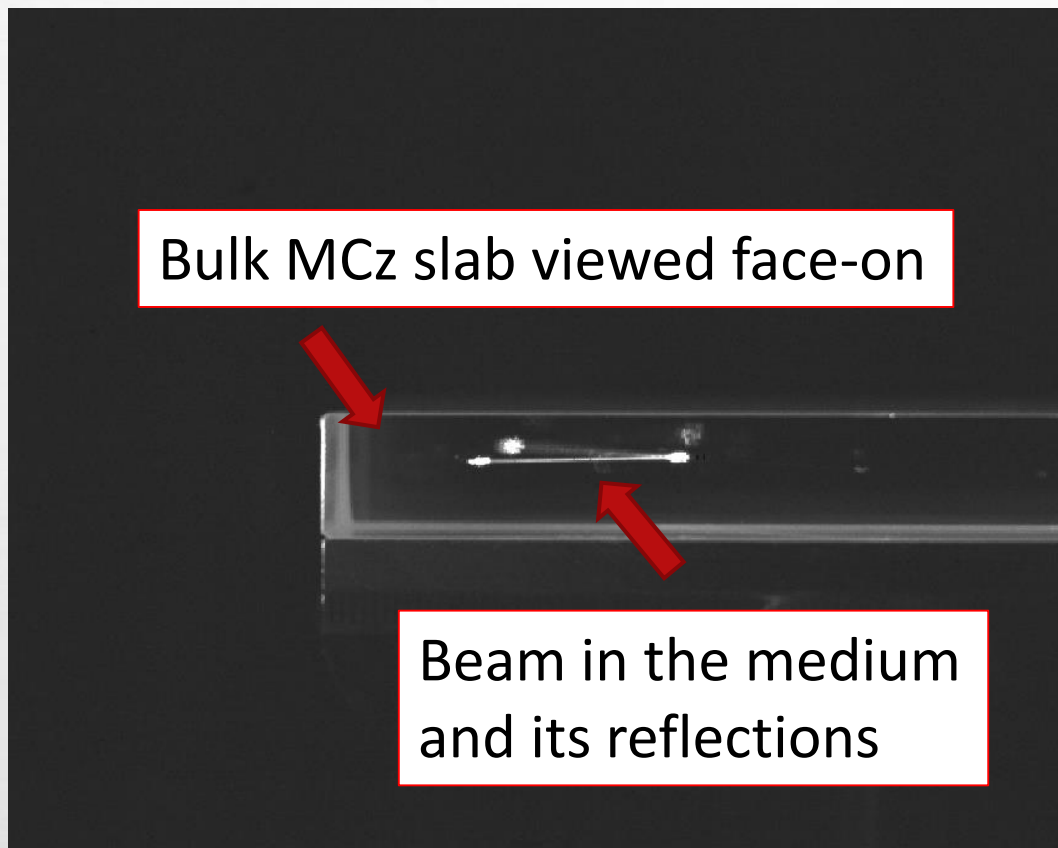
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MCz Si scatters  
at 1550 nm, at 16° observation angle:

0.11 - 0.17	ppm cm <sup>-1</sup> sr <sup>-1</sup>
0.99 - 1.6	ppm cm <sup>-1</sup>

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**45-74 ppm bulk scatter for a 46 cm thick test mass**  
**No requirement in ET design document**  
**Could be dominated by coating scattering\* finesse**

**“O1”: magnetic Czochralski silicon**



- Difficult to isolate the main beam from the many strong reflections (high refr index

Advanced LIGO

LIGO-T000127-v4

## LIGO Core Optics Components Design Requirements Document

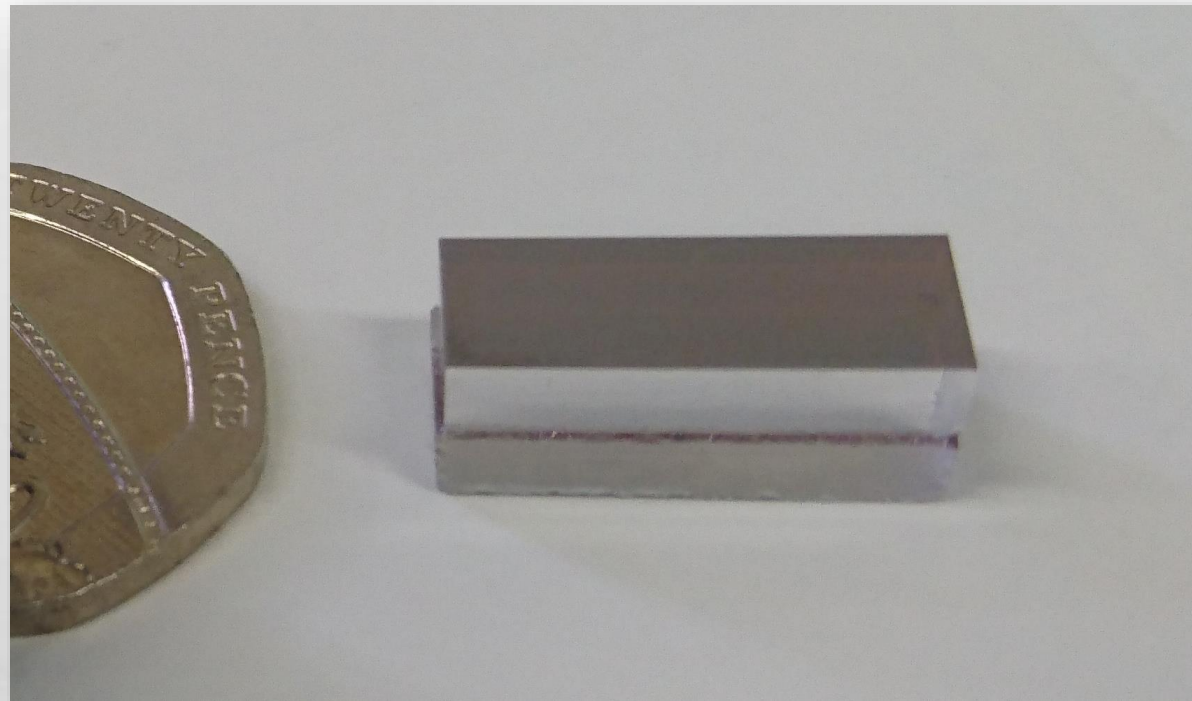
**Table 5 Specified limits to losses (in ppm) in COC optics**

Section reference	Loss Source	Input TM	End TM	BS Mirrors	Fold Mirror	Recycling Mirror
4.2.2.7.3	Bulk scattering of transmitted beams	<50	N/A	< 50	N/A	< 50

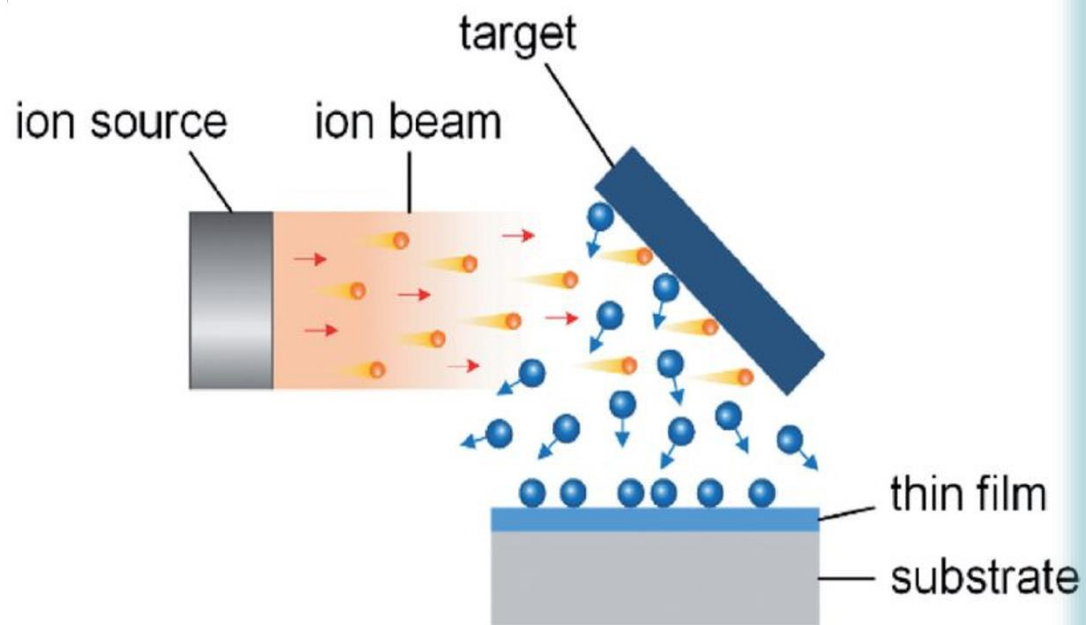
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# Amorphous silicon



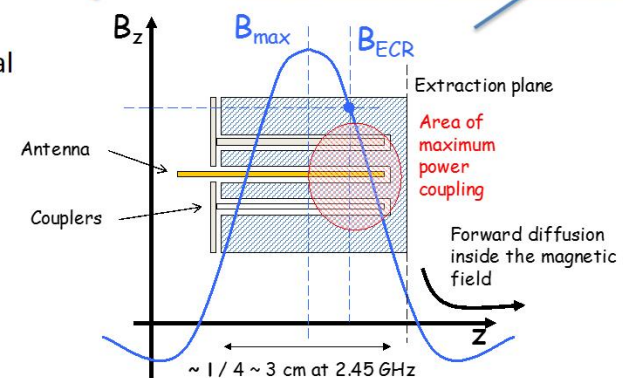
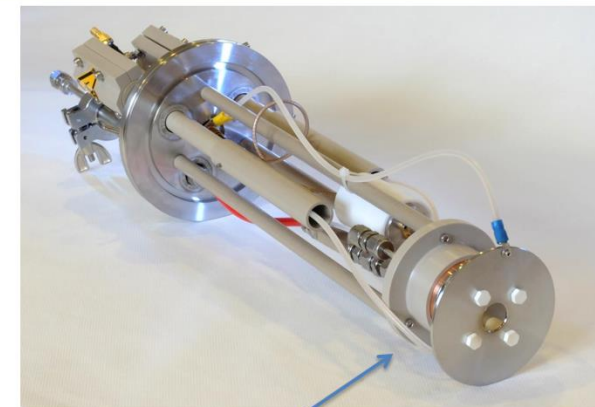
## ECR Ion Source

2.4GHz ECR ion source

Compact  $\lambda/4$  microwave resonant cavity

Advantages:

- Filament-free
- Gridless
- Maintenance free
- Low current
- 0-20kV extraction potential

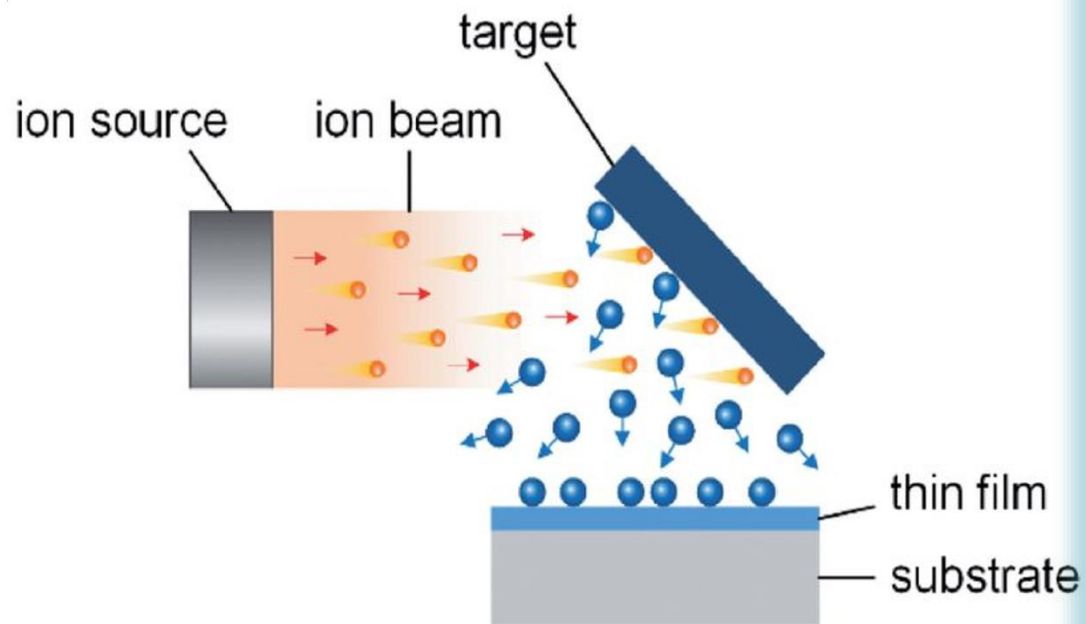


Slides courtesy of prof. Stuart Reid

# Heat deposited aSi films made at UWS

# Ion beam deposition (IBD)

First coatings: 20 ppm/QWL  
Very hard to reproduce!



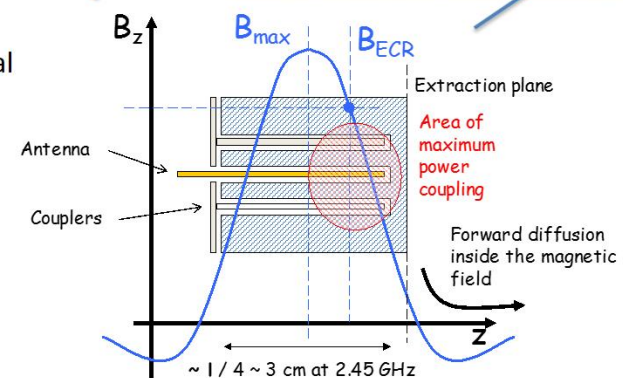
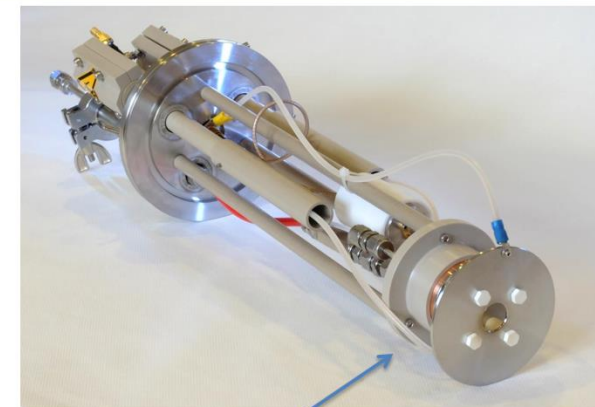
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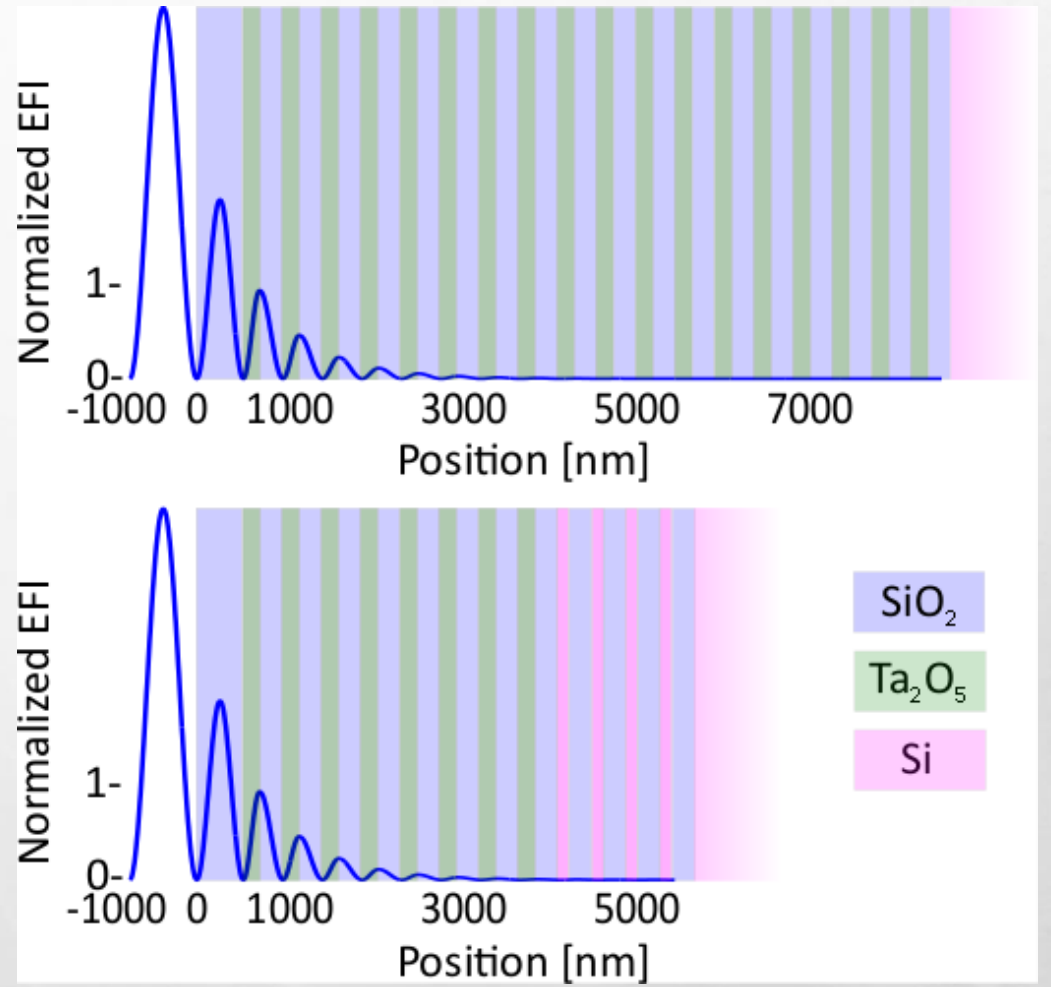
Slides courtesy of prof. Stuart Reid

# Heat deposited aSi films made at UWS

# Assuming aSi absorption 20 ppm/QWL at 1550nm

- We need 5 bilayers of SiO<sub>2</sub> and Ta<sub>2</sub>O<sub>5</sub> to reduce the laser power
- For an ITM with T= 6000 ppm we need 2 bilayers of SiO<sub>2</sub> and aSi
- For an ETM with T = 6 ppm we need 5 bilayers of SiO<sub>2</sub> and aSi
- Thermal noise improvement\* compared to a pure SiO<sub>2</sub> and Ta<sub>2</sub>O<sub>5</sub> coating:

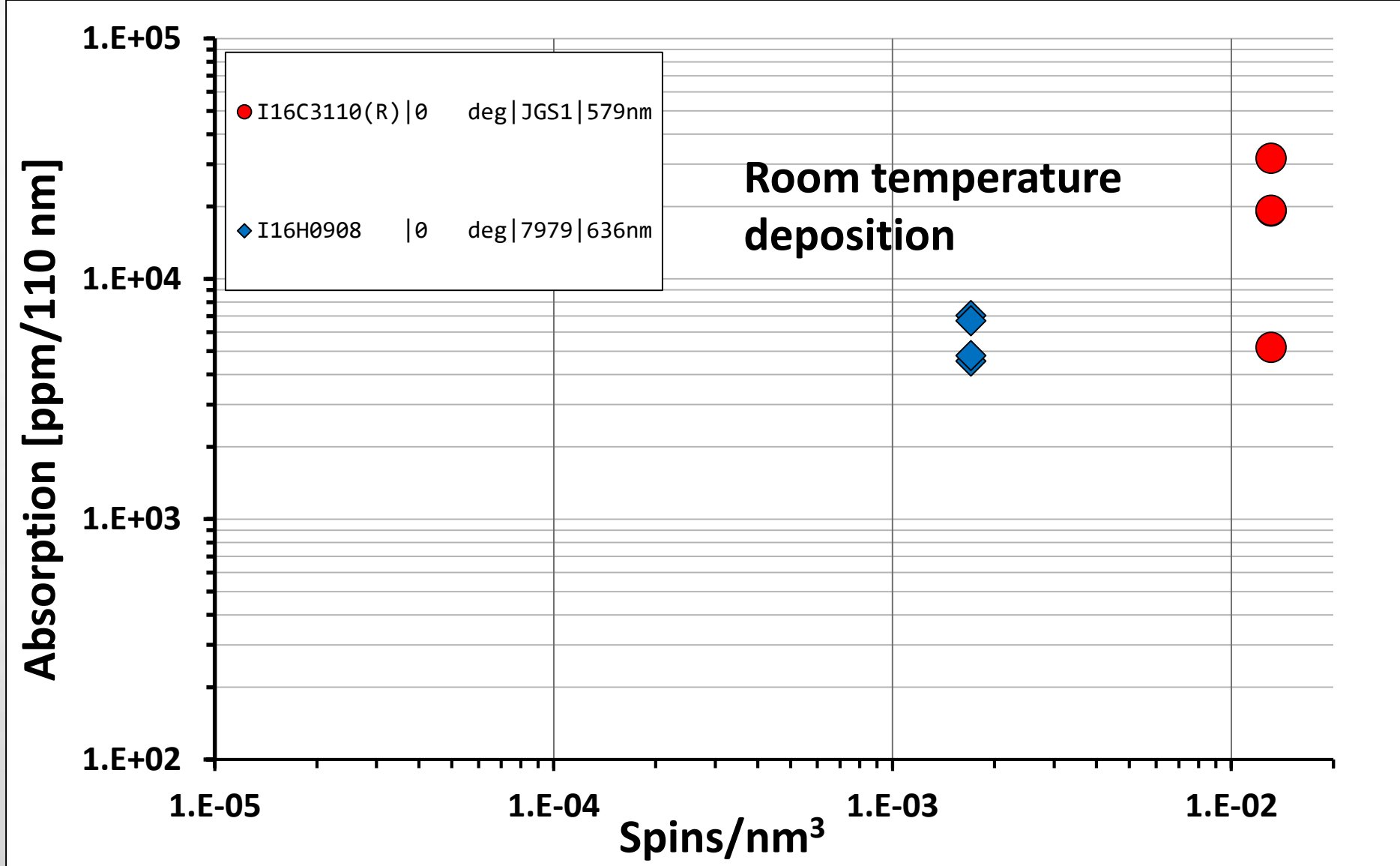
<b>120 K</b>	<b>20 K</b>
ITM: -21%	-20%
ETM: -38%	-36%
<b>total: -32%</b>	<b>-31%</b>



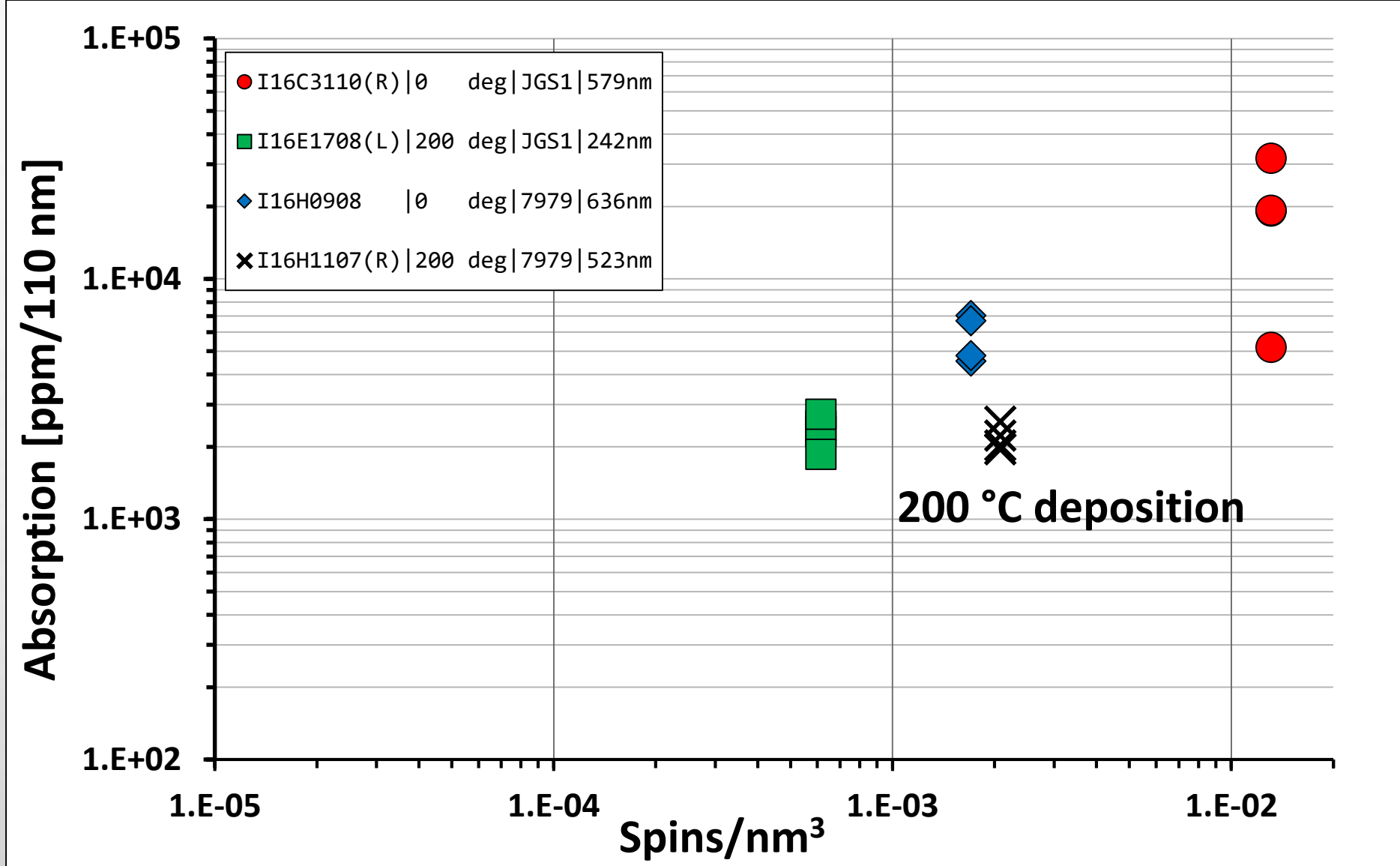
\*Loss for aSi: values from commercial coatings; no cryogenic measurements on UWS coatings

Simulations: J. Steinlechner

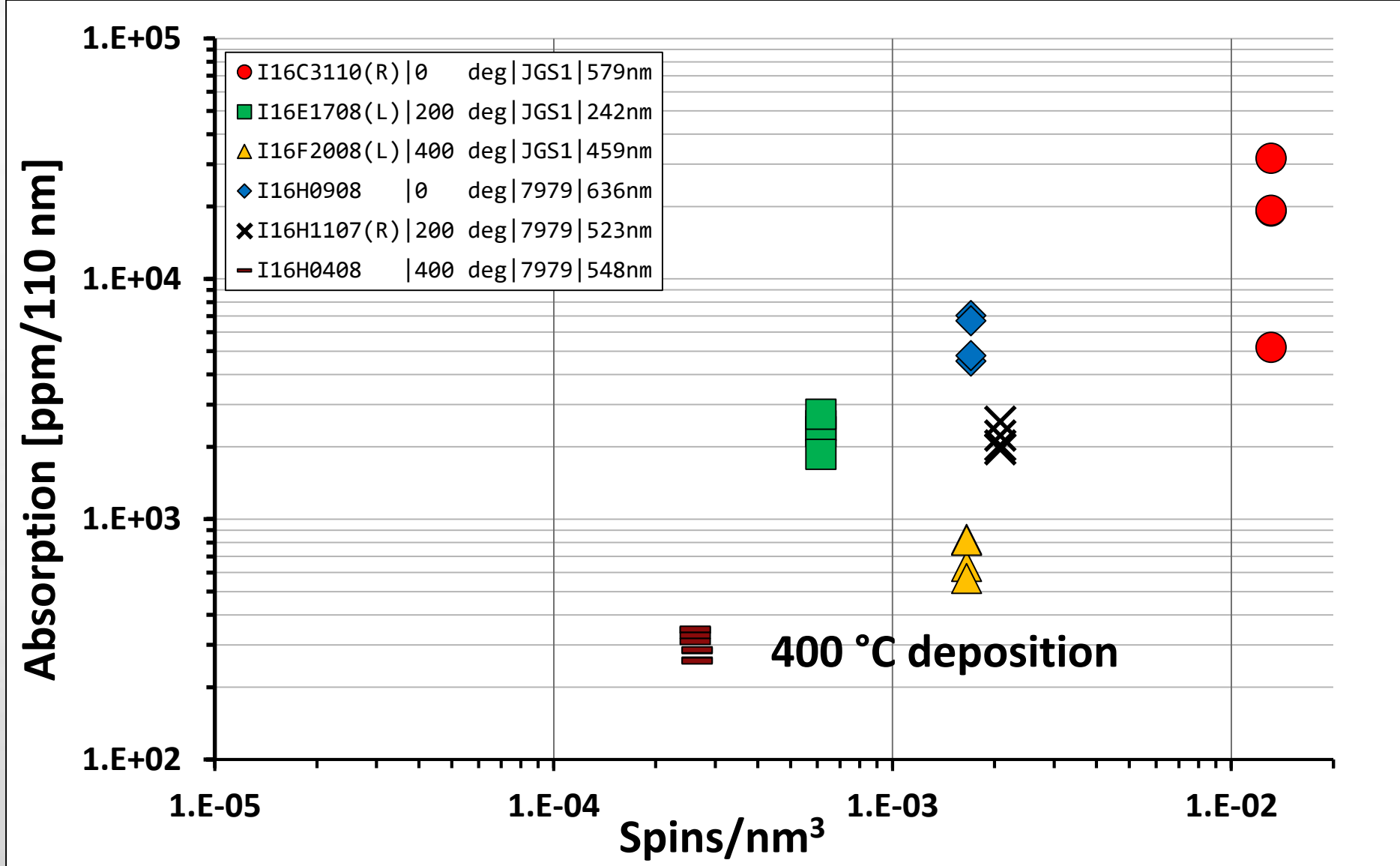
# Multimaterial coating with aSi



# Dangling bonds - absorption correlation

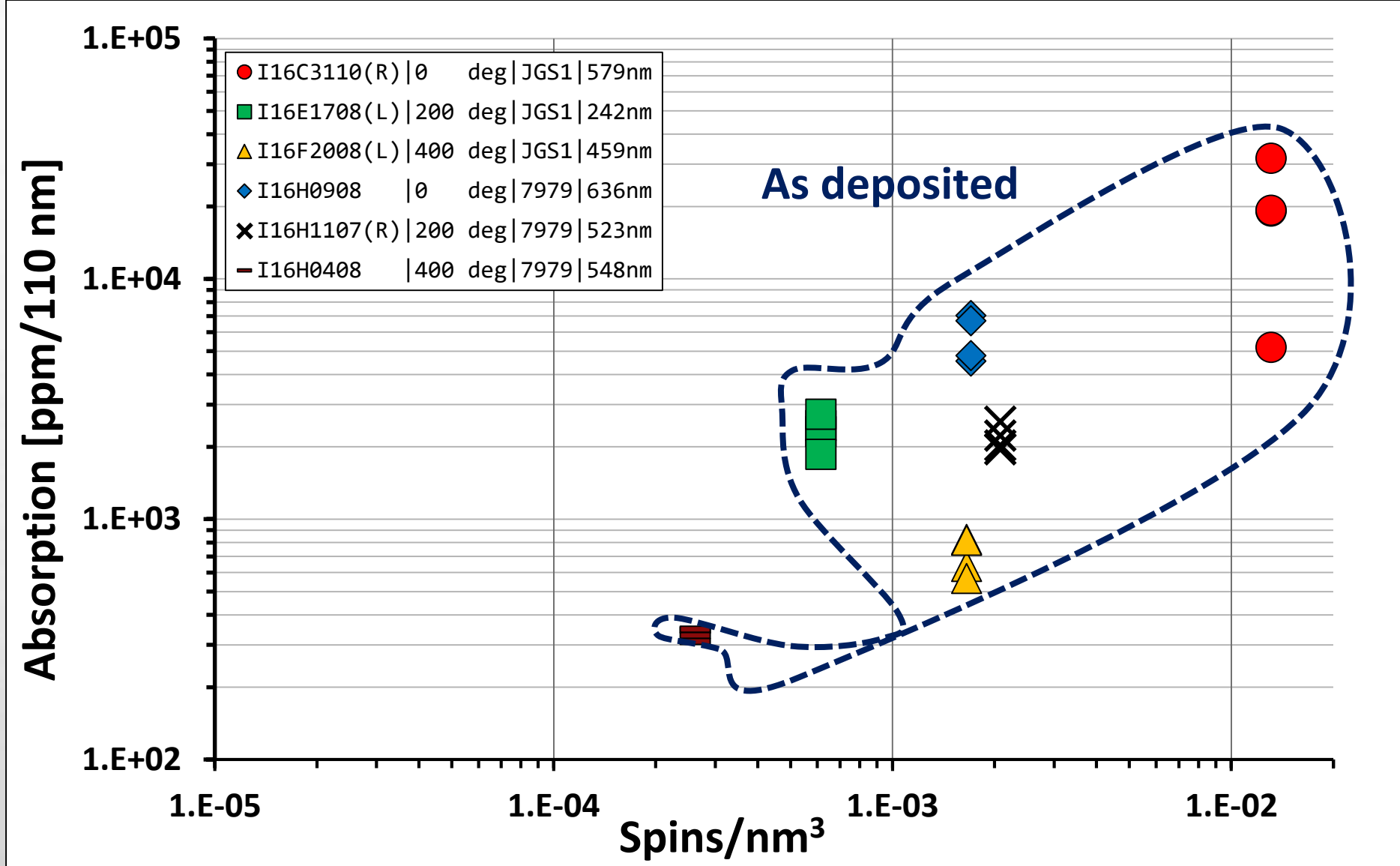


# Dangling bonds - absorption correlation



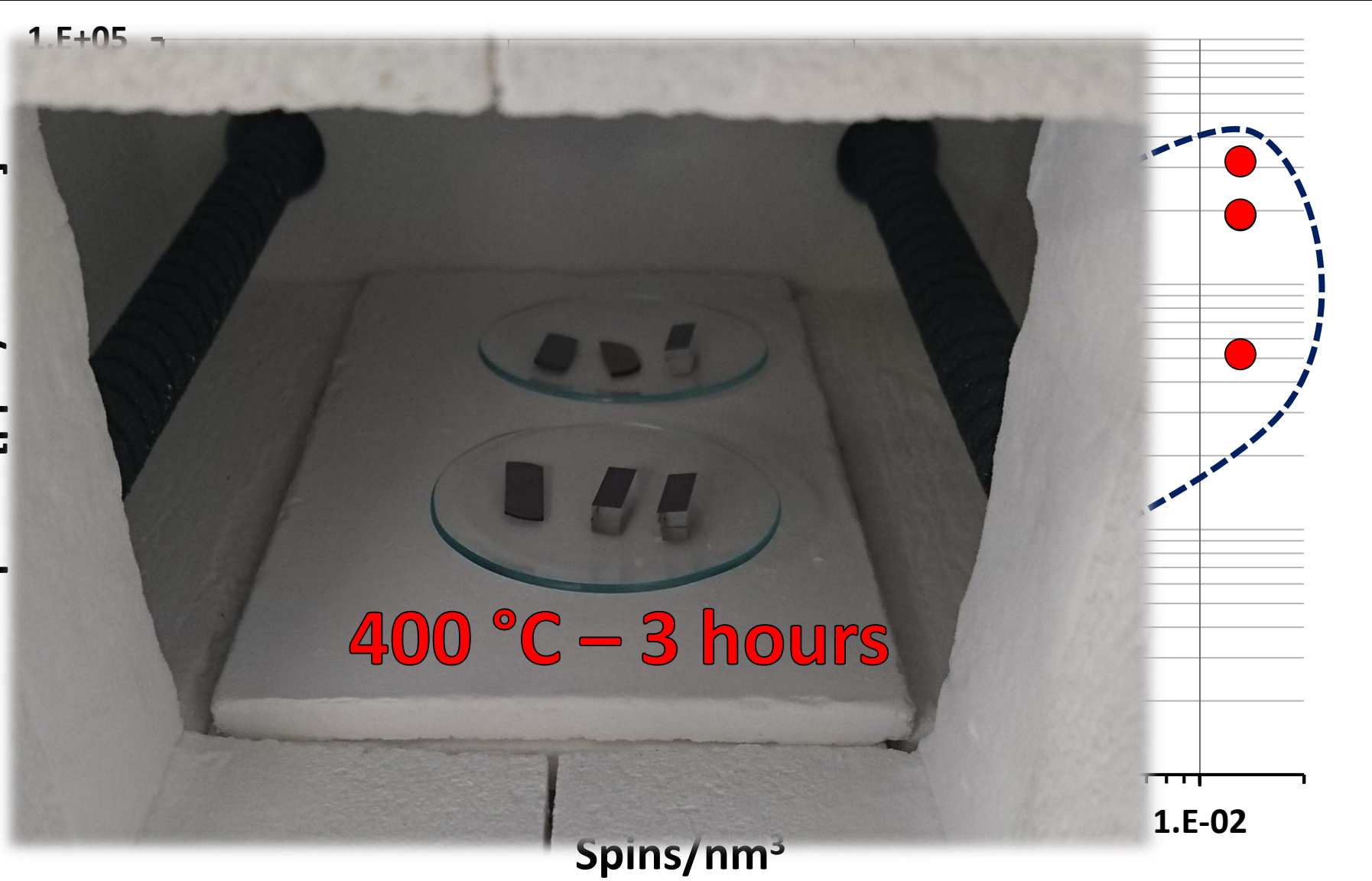
# Dangling bonds - absorption correlation





# Dangling bonds - absorption correlation

Absorption [ppm/110 nm]



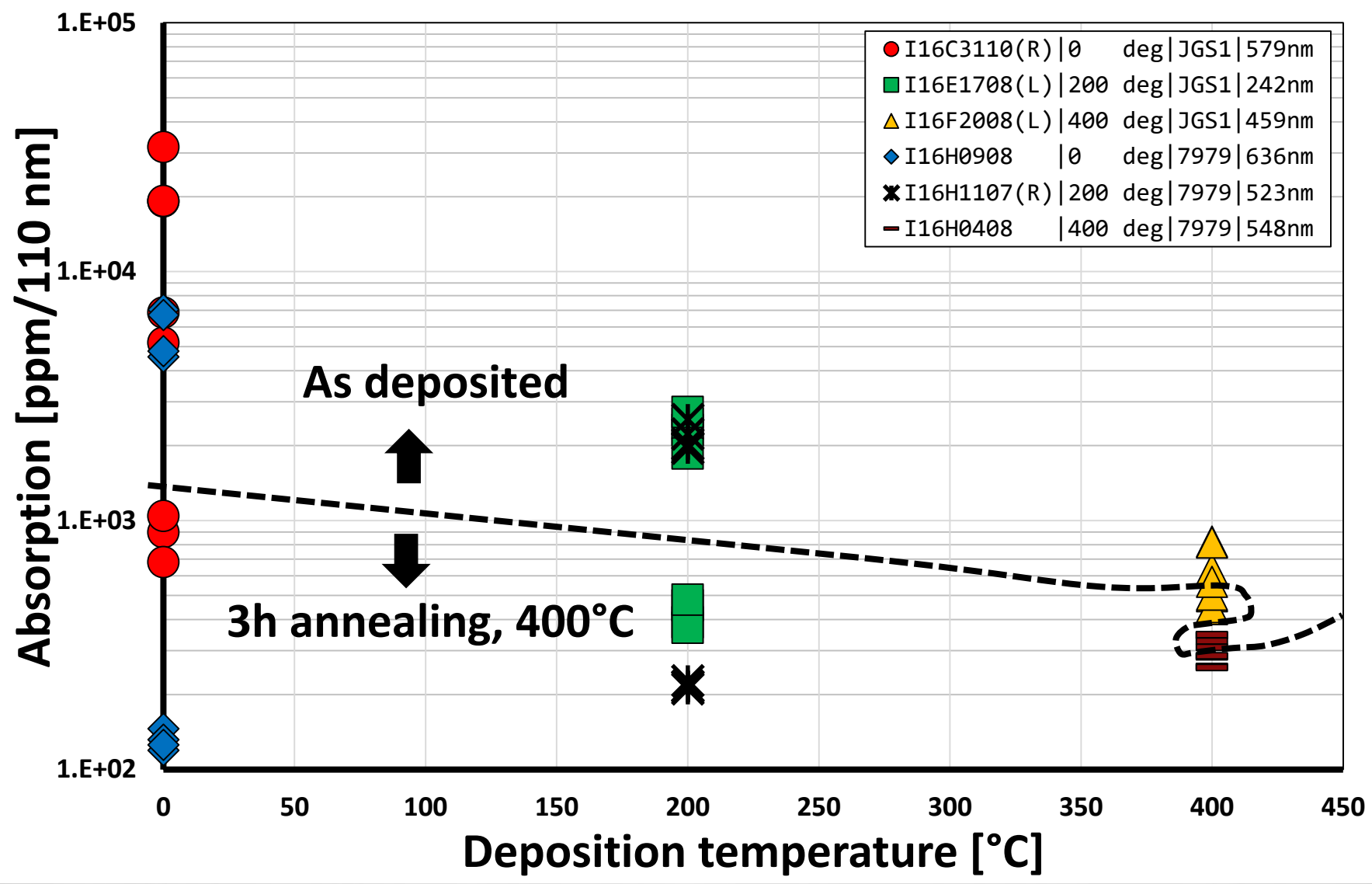
400 °C – 3 hours

Spins/nm<sup>3</sup>

1.E-02

# Dangling bonds - absorption correlation

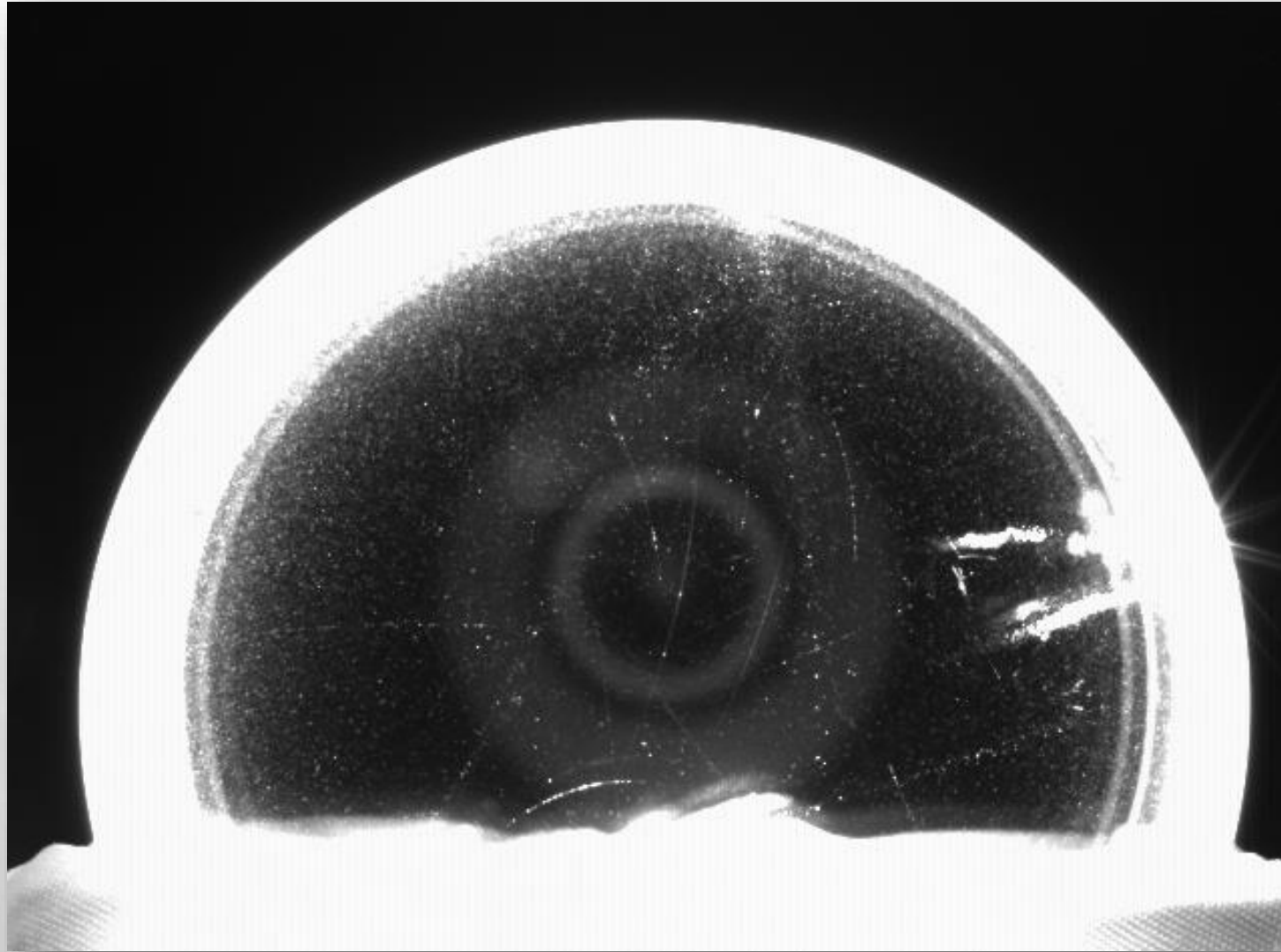




# Deposition temperature - absorption correlation

1. Silicon is a promising material for cryogenic GW core optics.
2. It has low mechanical loss at low temperature, zeros of expansion coefficient, high refractive index
3. In Glasgow a scatterometer is active
4. It is able to take measurements to better than order of magnitude level but we're working hard towards a fully reliable instrument
5. **Preliminary measurement of MCz Si bulk scattering suggests that might be compatible with use in ET -- 45-74 ppm bulk scatter for a 46 cm thick test mass could be just as high as we can afford**
6. Heat deposited aSi coatings show absorption comparable with annealed ones (but better mechanical loss).
7. A clear link has been established between absorption and dangling bonds, and absorption and deposition temperature.

## Conclusions



**Thank you!**

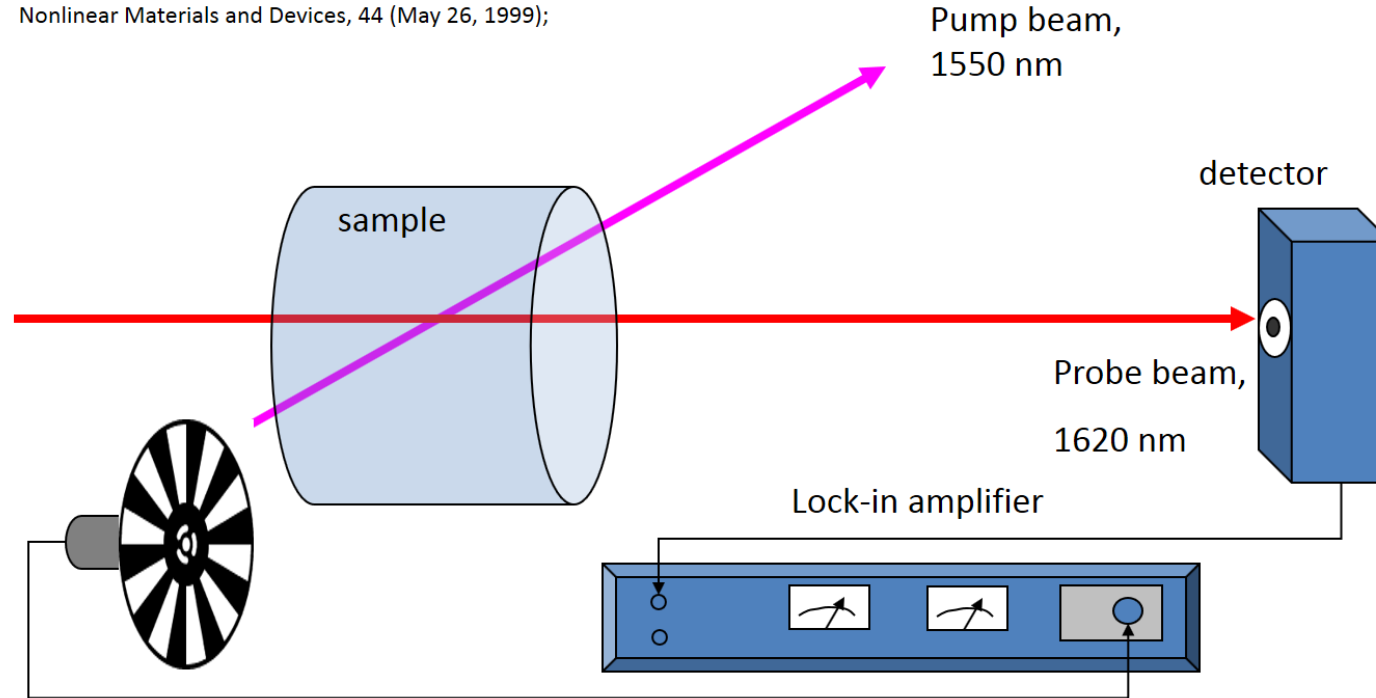
1. Optimise the scatterometer, understand its noise sources and discrepancies with literature
2. Carry out systematic angle-dependent measurements to verify to which extent the scattering observed is really only Rayleigh
3. Find a way to reliably calibrate the system
4. Work towards understanding surface absorption (not discussed here)
5. Integrate the aSi coatings study with other analyses such as Raman spectroscopy

**Future**

# Absorption measurements - IGR

## Photo-thermal commonpath interferometry (PCI)

A. Alexandrovski et al. *Proc. SPIE* 3610, Laser Material Crystal Growth and Nonlinear Materials and Devices, 44 (May 26, 1999);

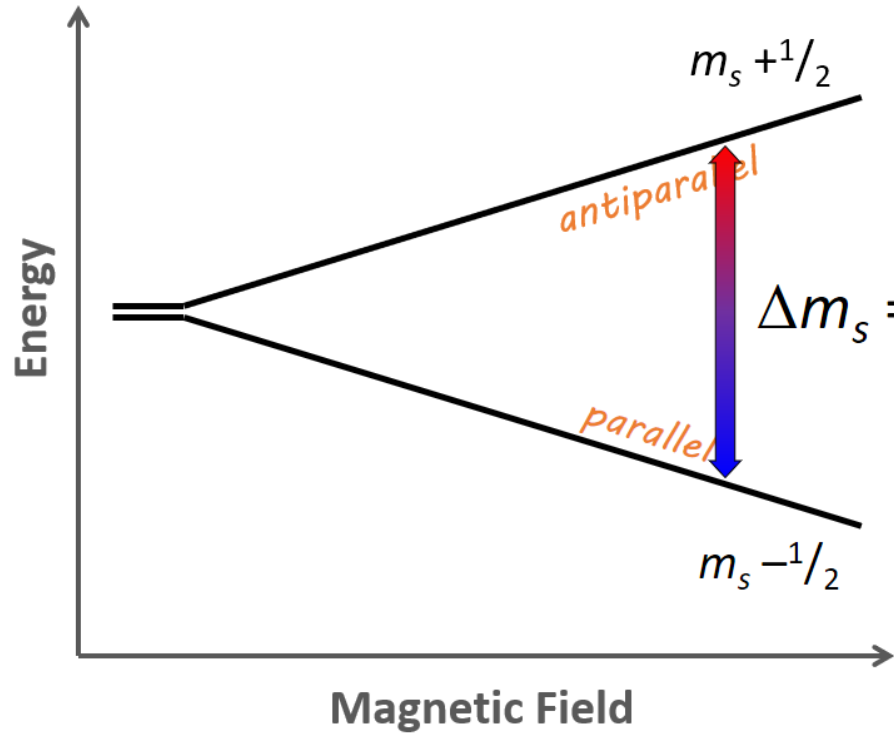


# Photothermal common-path interferometry (PCI)



# Electron Paramagnetic Resonance

Magnetic field (B) splits the degeneracy of two  $m_s$  states – Zeeman effect



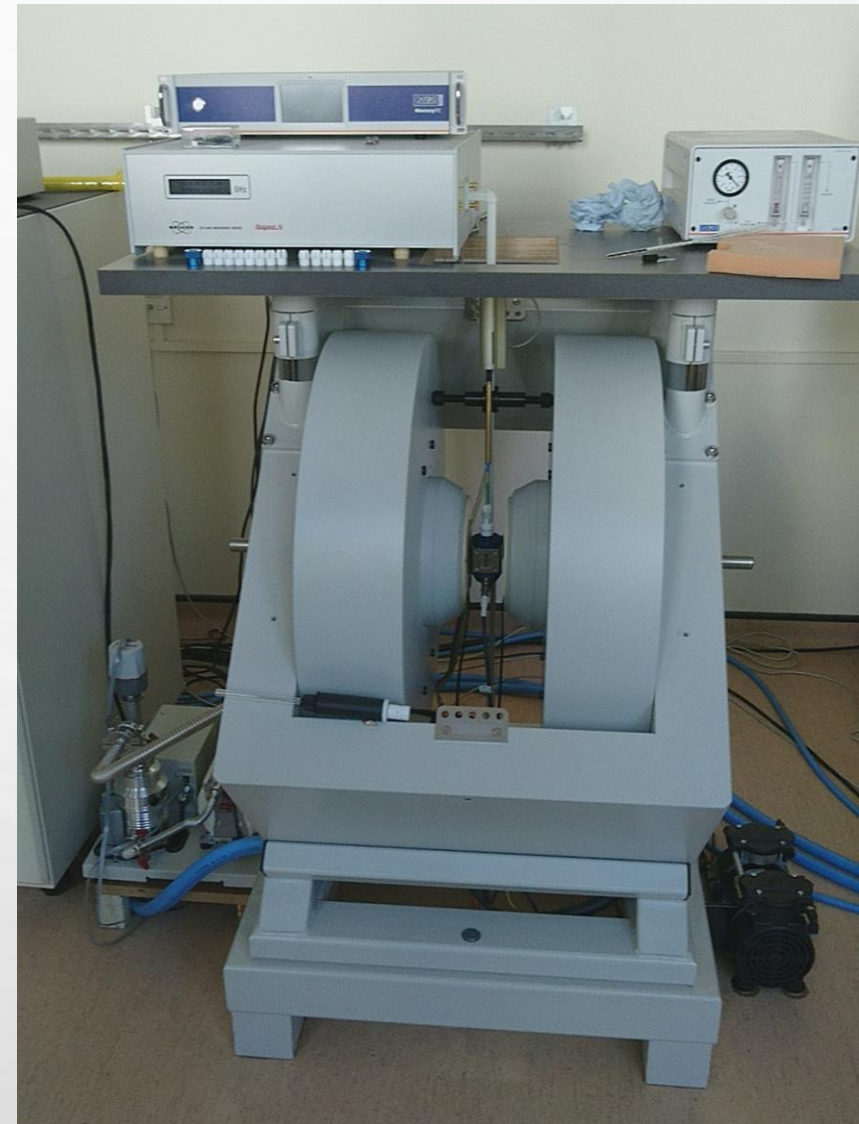
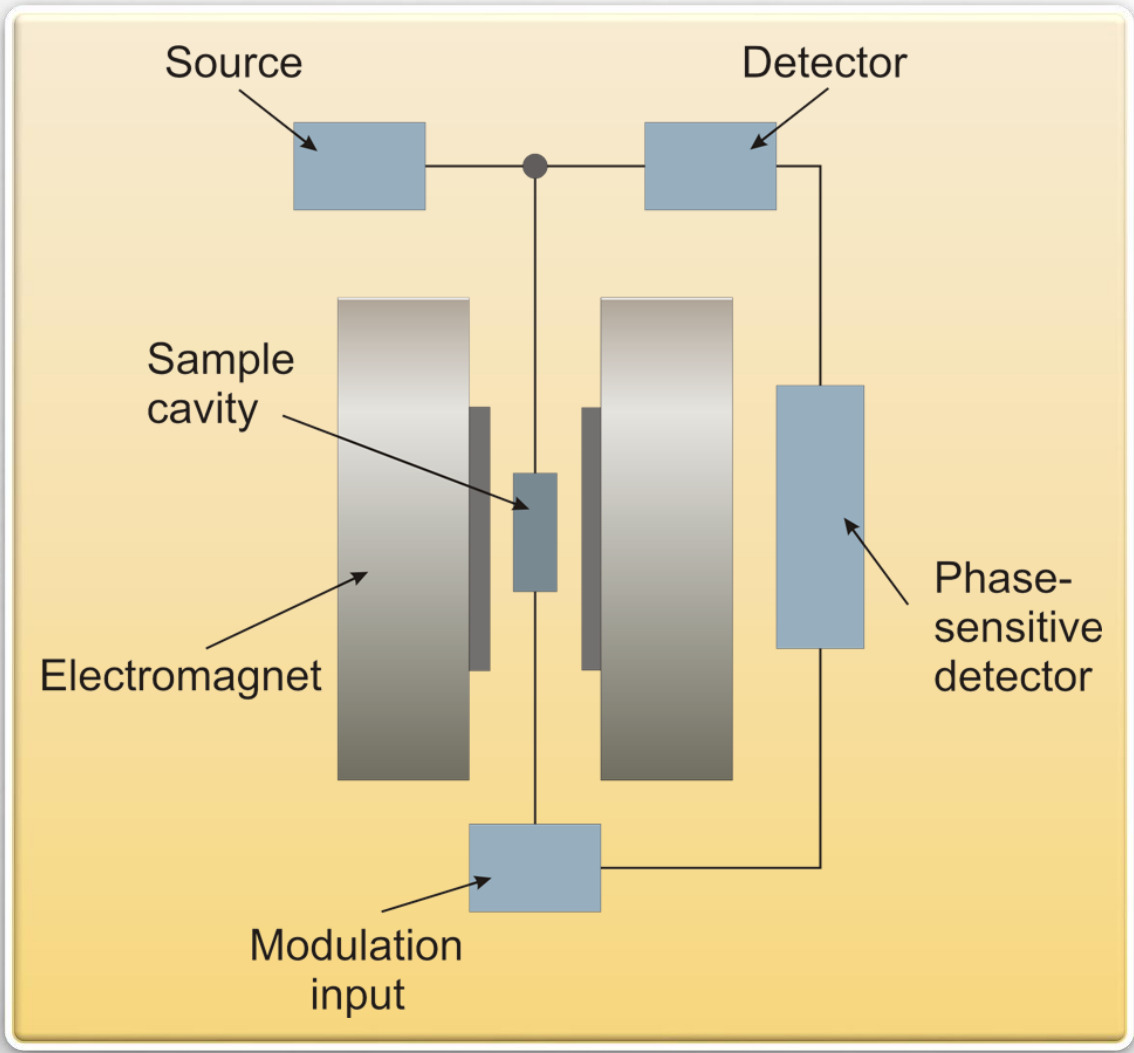
EPR measures the transition between these electron spin ( $m_s$ ) energy levels

*EPR selection rule*

Required frequency of radiation dependent upon strength of magnetic field

- Common field strength 0.34 T
- corresponds to 9.5 GHz (X-band)

**EPR – Courtesy of Stephen Sproules**



# EPR – Courtesy of Stephen Sproules

At 1064 nm RT:

- We need 8 bilayers of  $\text{SiO}_2$  and  $\text{Ta}_2\text{O}_5$  to reduce the laser power
- For an ITM with  $T= 1.4\%$  we can't improve the coating using aSi in lower layers
- For an ETM with  $T = 6 \text{ ppm}$  we need 4 bilayers of  $\text{SiO}_2$  and aSi
- Thermal noise improvement\* compared to a pure  $\text{SiO}_2/\text{Ta}_2\text{O}_5$  coating:

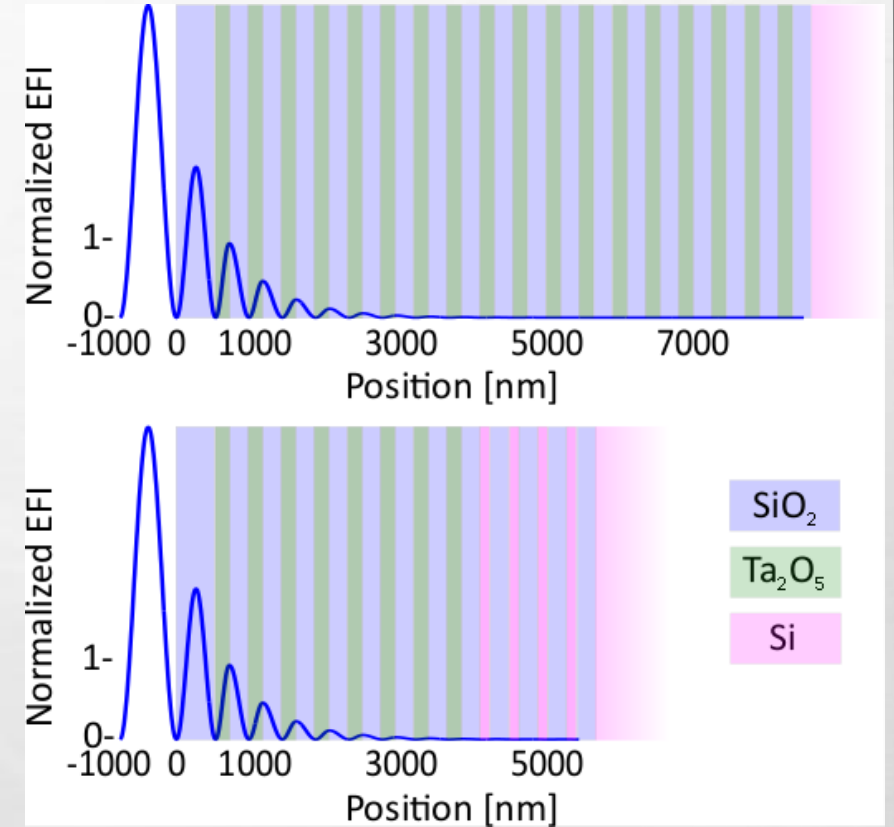
Room temperature:

ITM: - 0%

ETM: - 28%

**total: -22%**

**Almost no improvement by reducing mechanical loss further (limited by silica loss and ITM thermal noise)**



\*Loss for aSi: values from commercial coatings; no cryogenic measurements on UWS coatings

Simulations: J. Steinlechner

**EPR – Courtesy of Stephen Sproules**